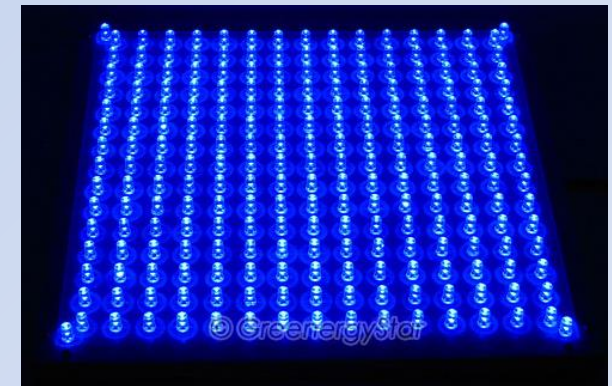
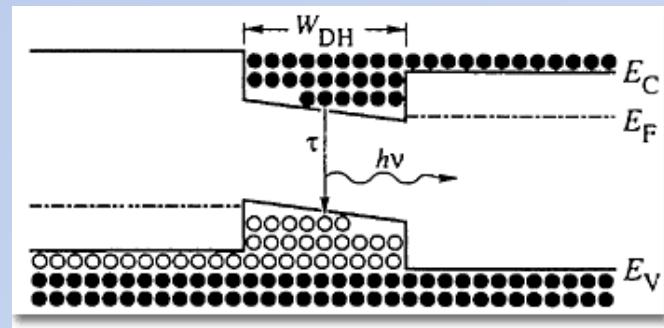
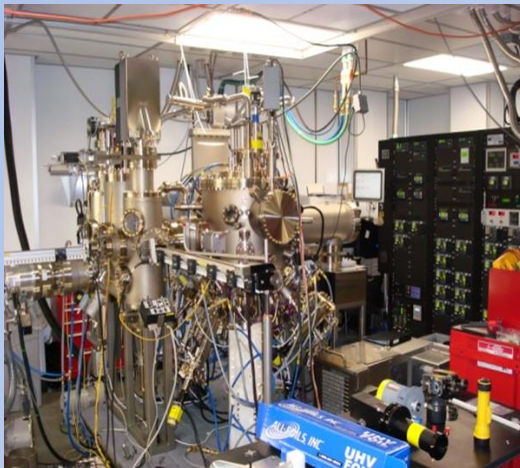


The Art and Science of Molecular Beam Epitaxy and the Nobel Prize for Blue LEDs

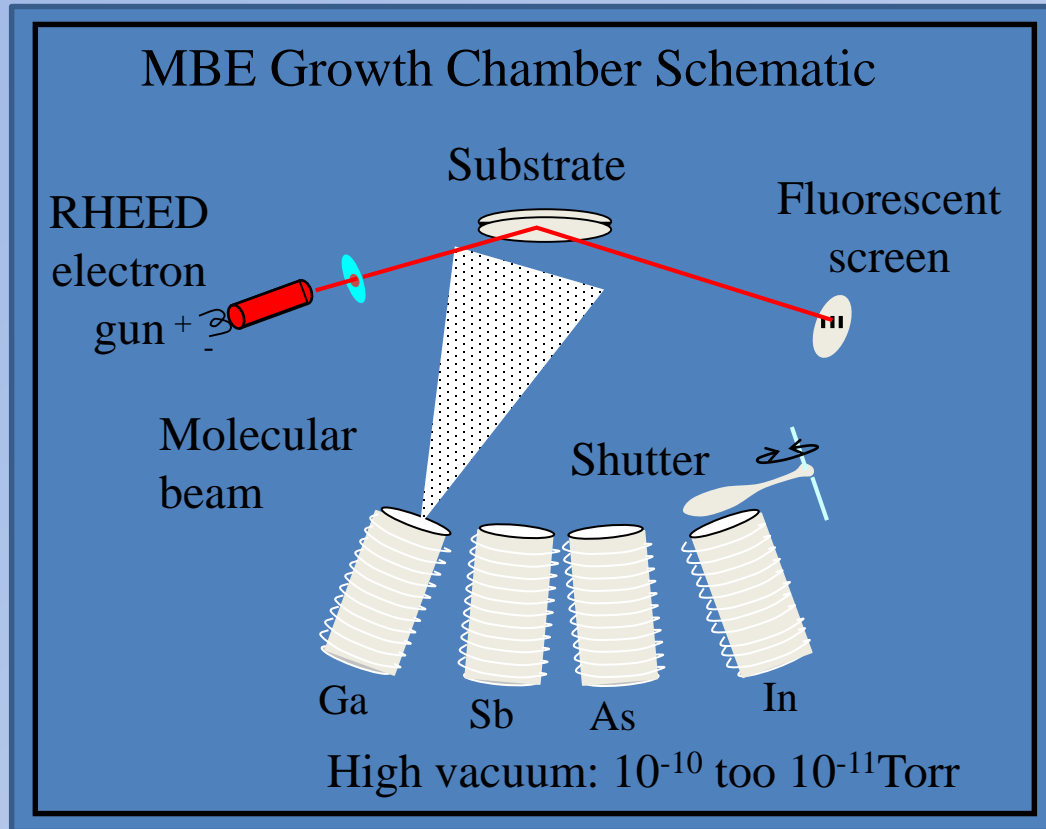
John Prineas

Department of Physics and Astronomy, University of Iowa

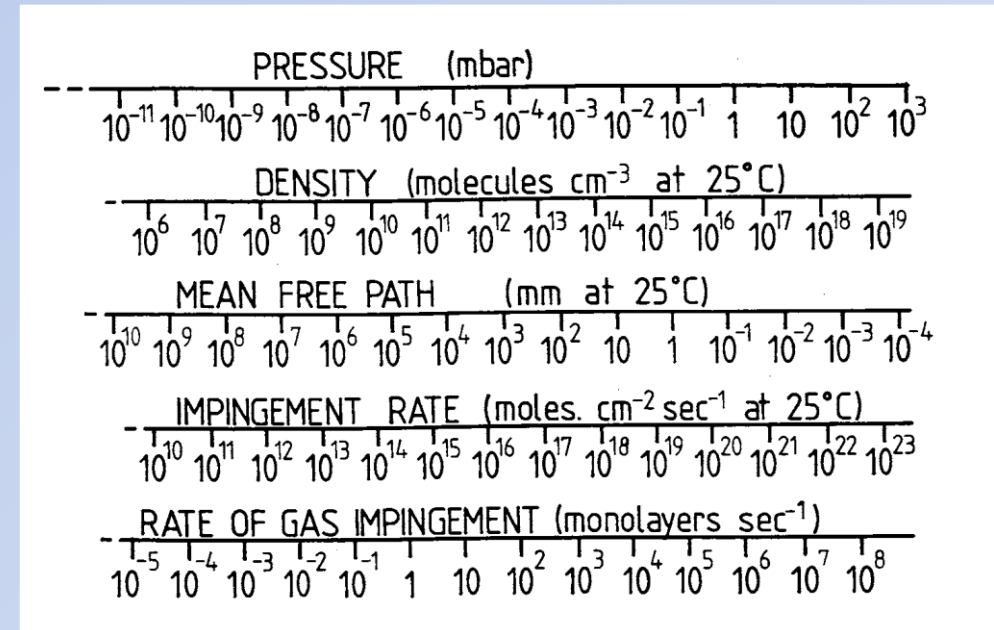
Oct 20, 2014



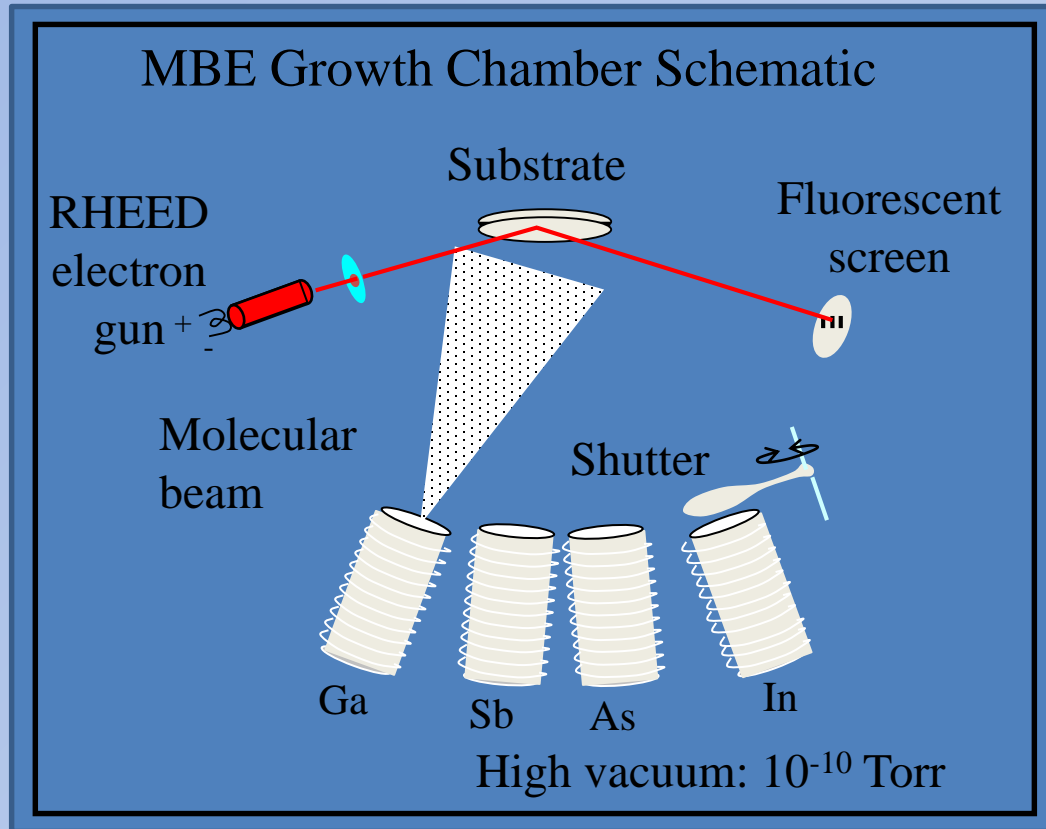
What is molecular beam epitaxy? An ultrahigh vacuum technique for deposition of atoms on a crystalline substrate to form crystalline layers or structures



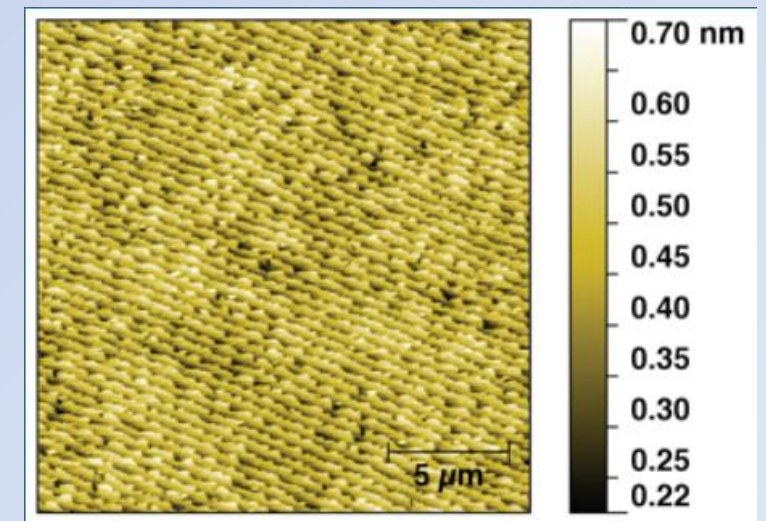
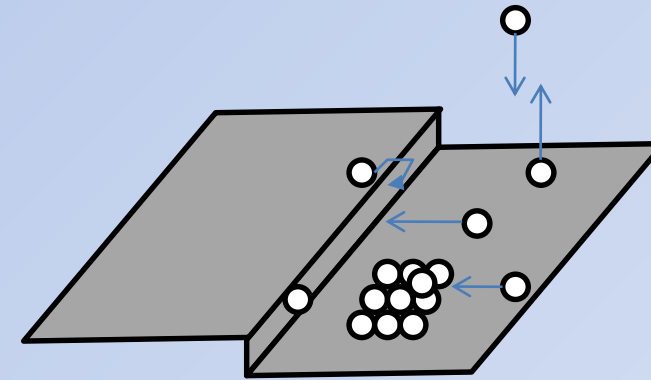
Why ultrahigh vacuum?



What is molecular beam epitaxy? An ultrahigh vacuum technique deposition of atoms on a crystalline substrate to form crystalline layers or structures

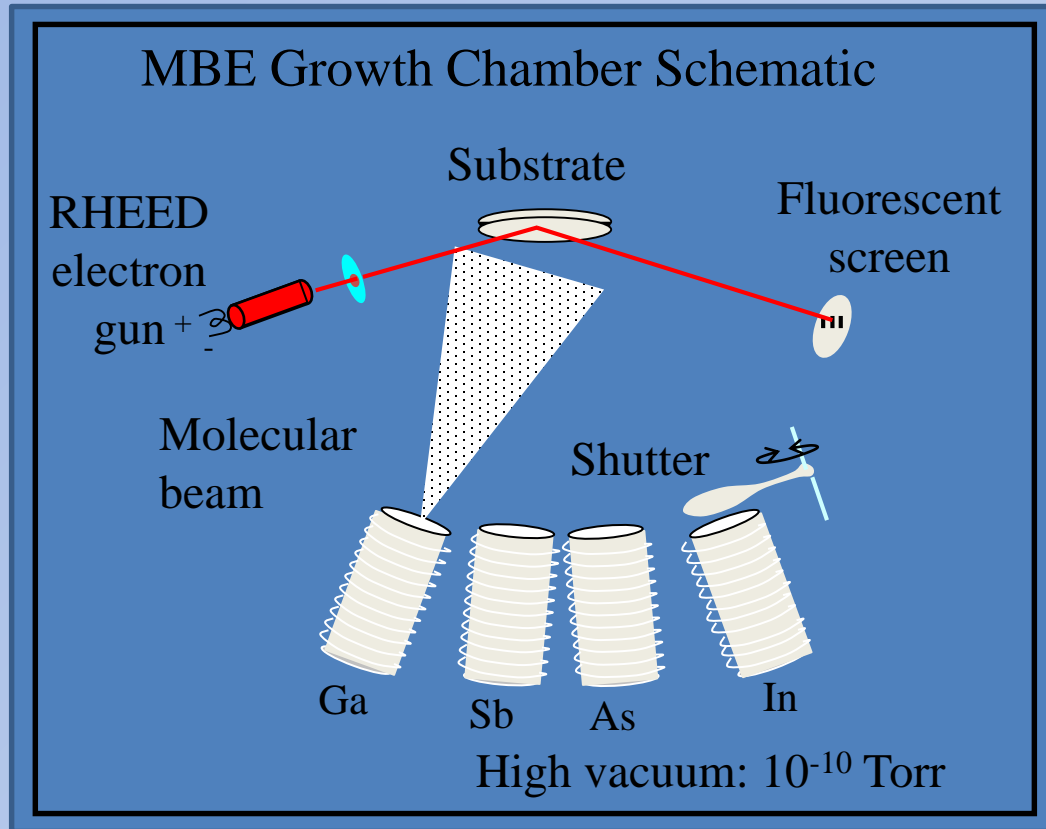


Deposition of compound semiconductor layers with single atomic layer precision

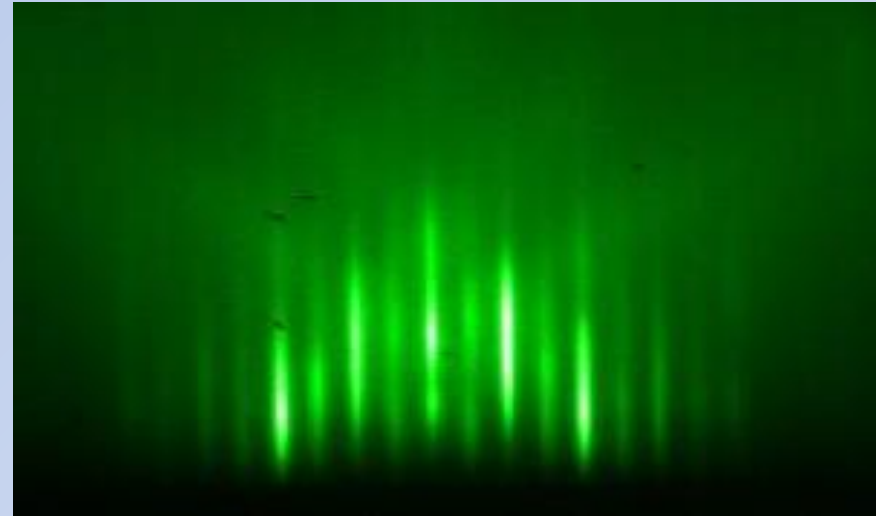


Step flow across a GaSb MBE layer

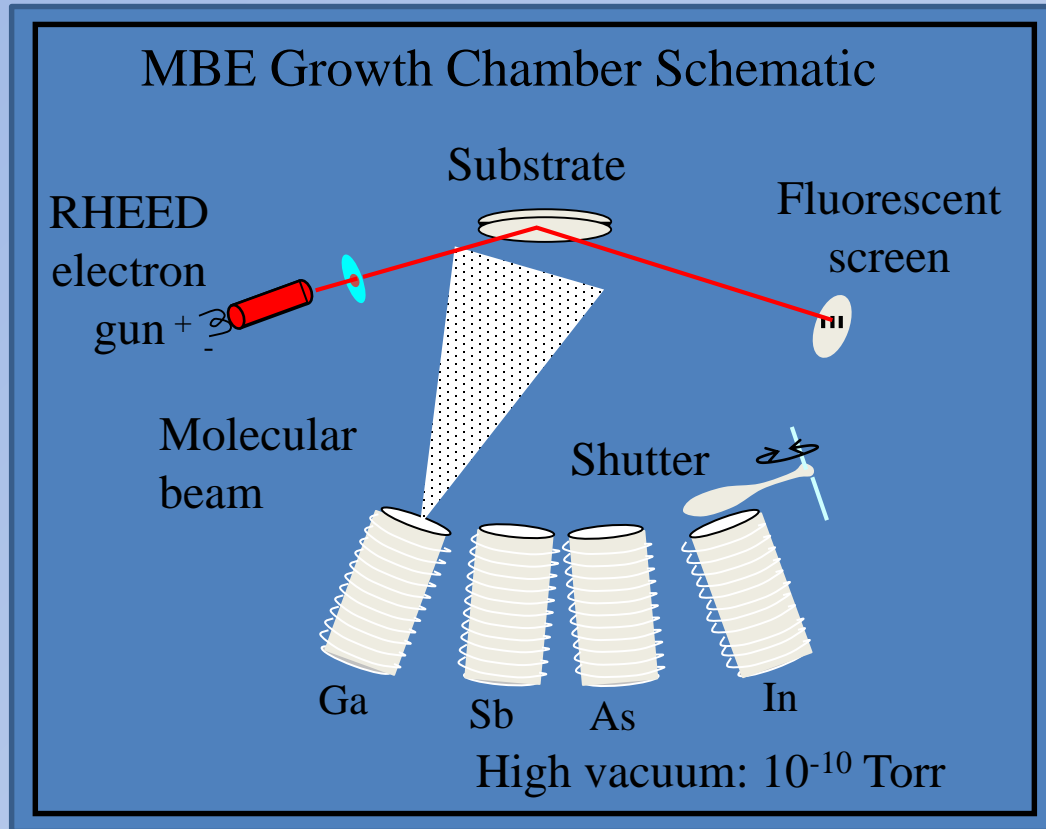
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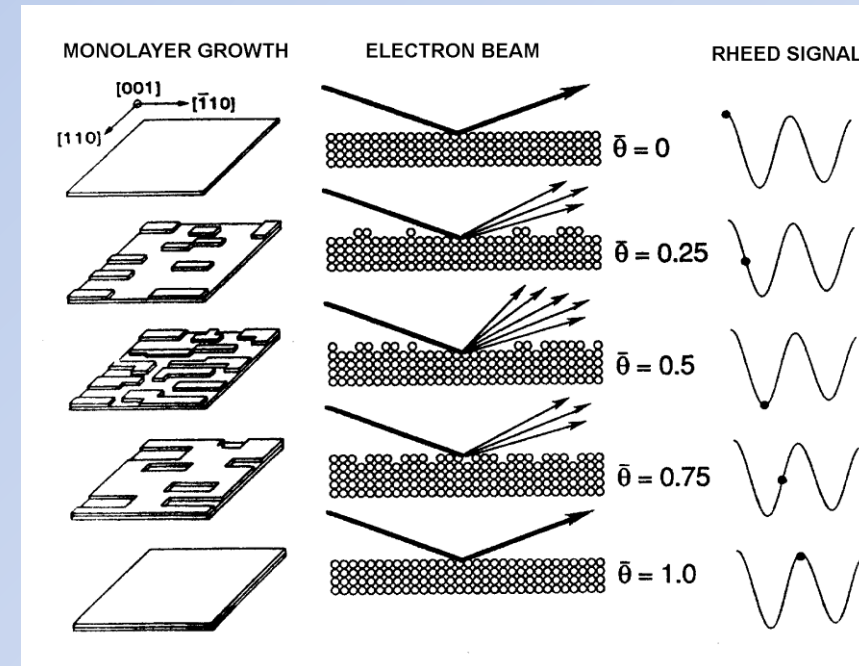
Reflection high energy electron diffraction



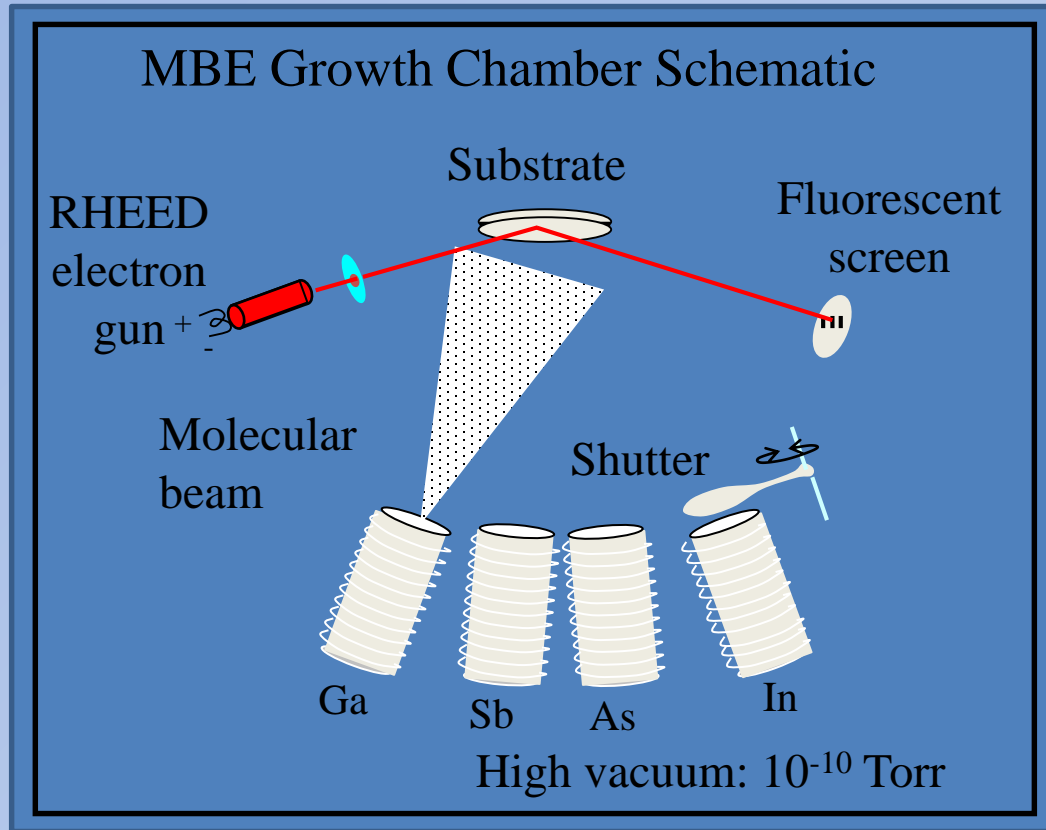
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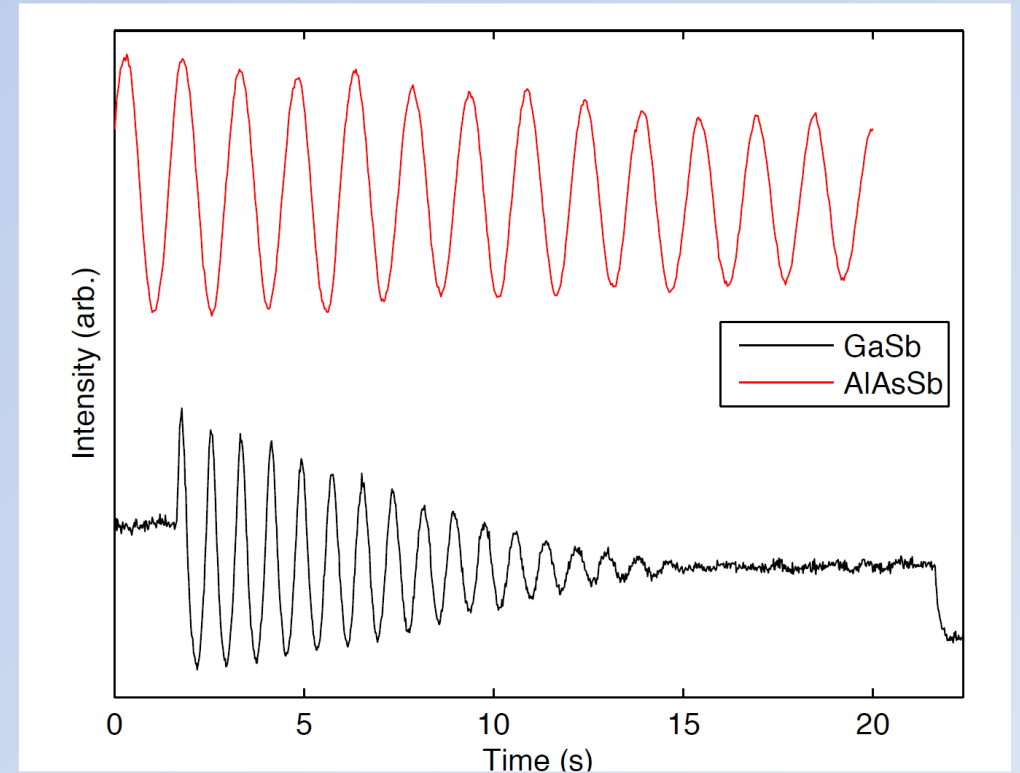
Reflection high energy electron diffraction



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Reflection high energy electron diffraction

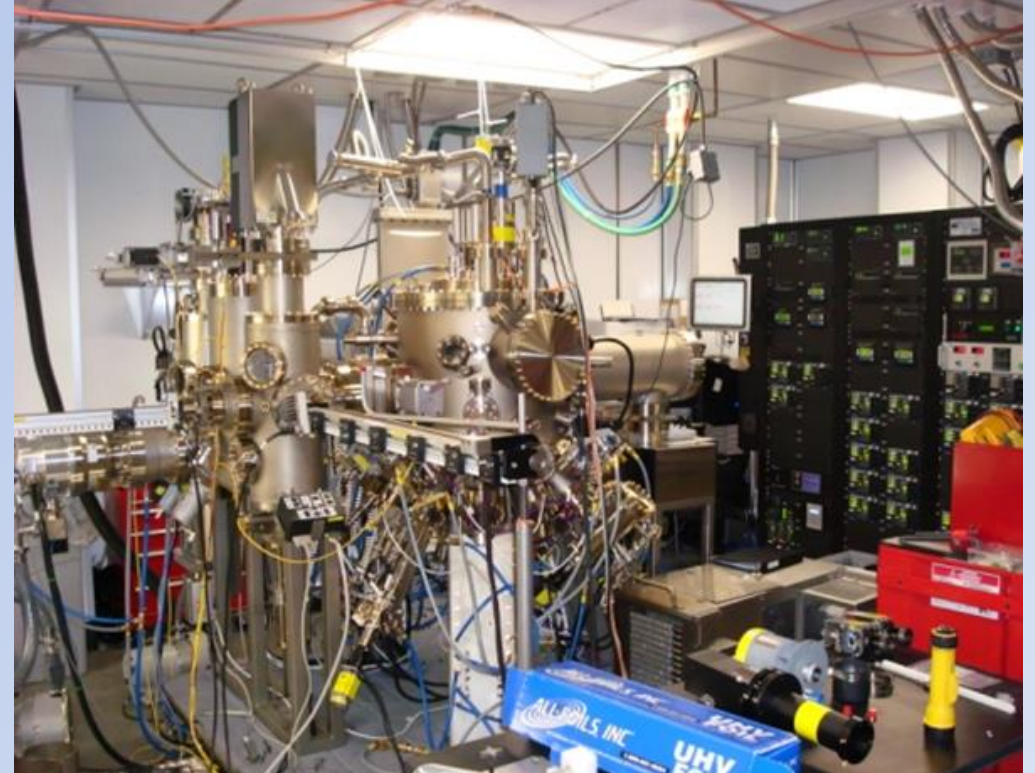


A quick tour of the MBE facilities at the University of Iowa:

EPI930



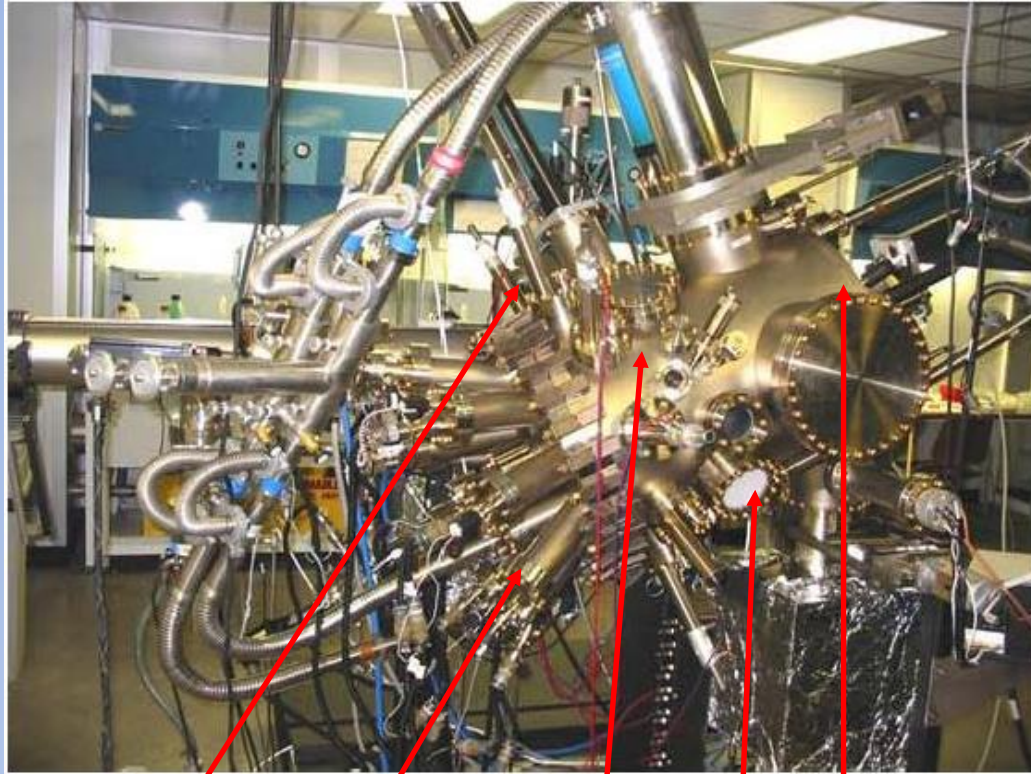
GEN20



Commercial VEECO machines from headquarters in Minneapolis, MN; one of two principle worldwide suppliers, along with Riber

A tour of the MBE facilities at the University of Iowa:

EPI930



Shutter control

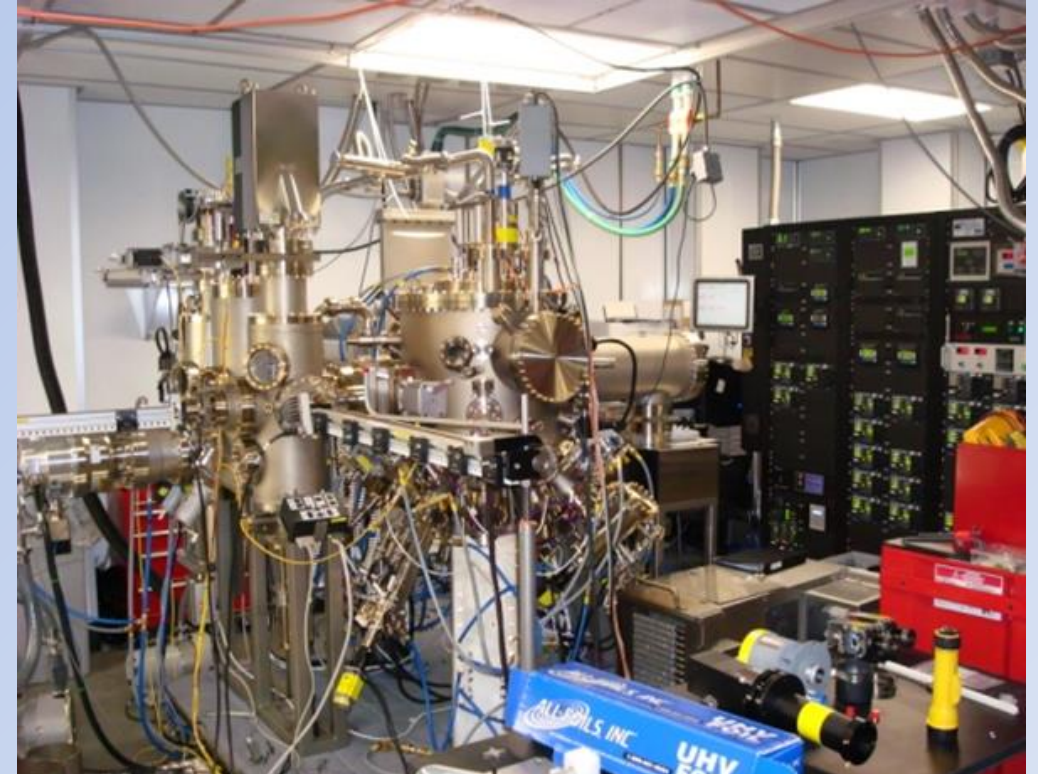
High purity sources

Vacuum chamber

Substrate manipulator

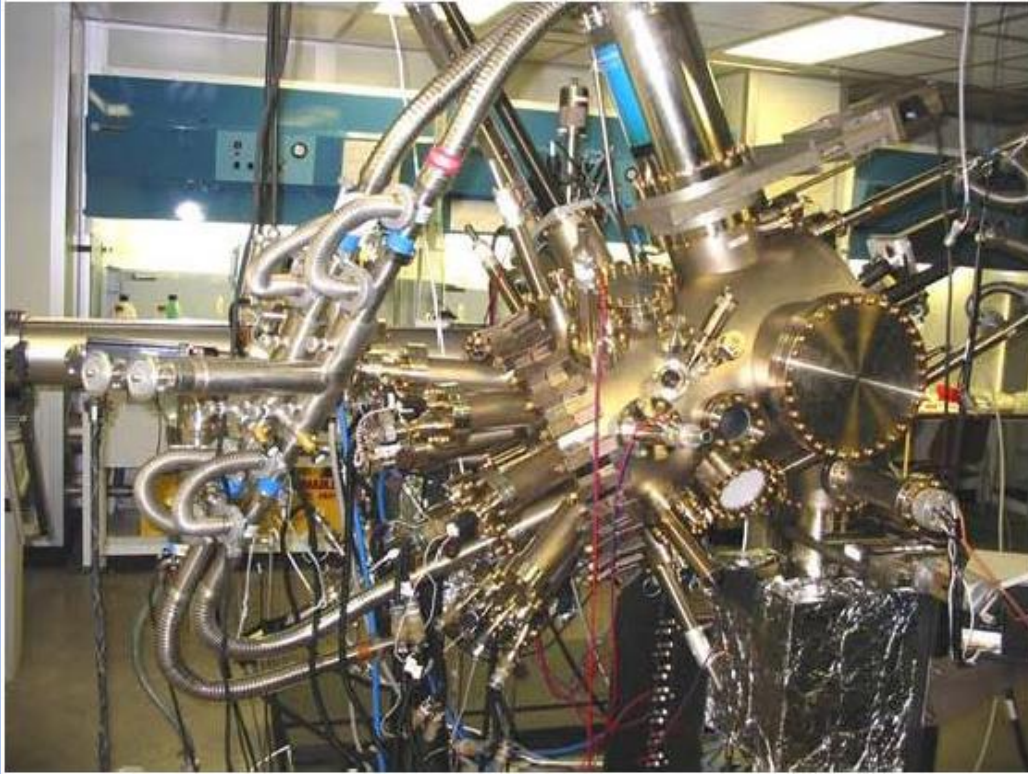
RHEED screen

GEN20

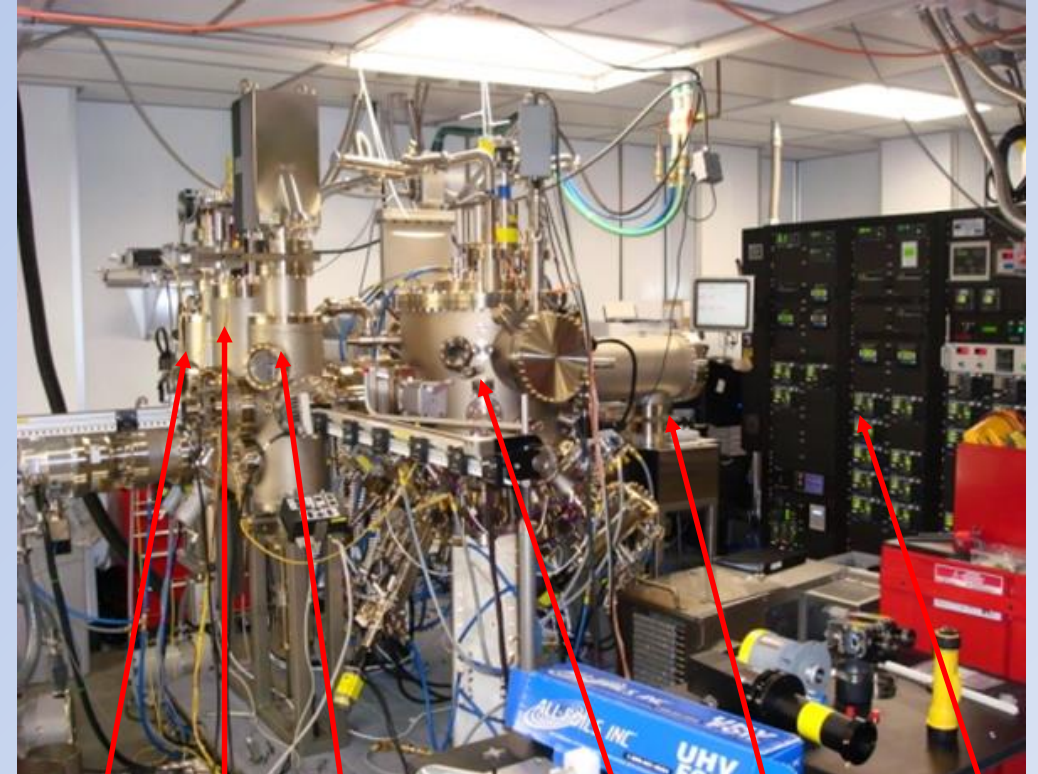


A tour of the MBE facilities at the University of Iowa:

EPI930



GEN20



Intro chamber

Prep chamber

Storage chamber

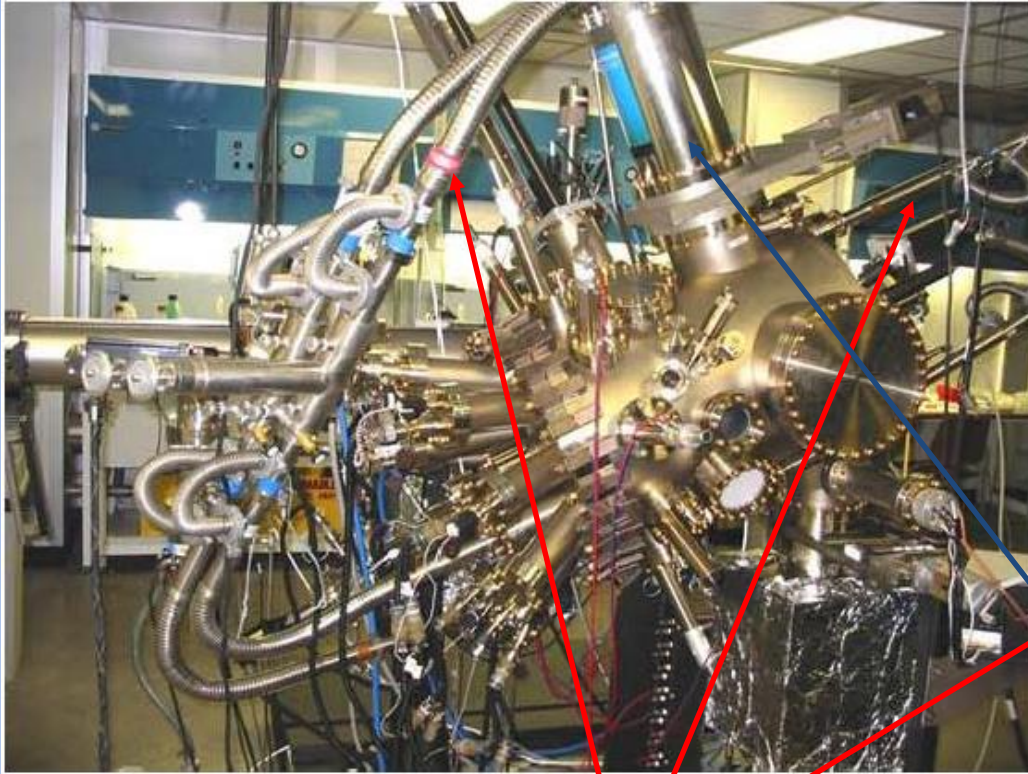
Growth chamber

Computer control

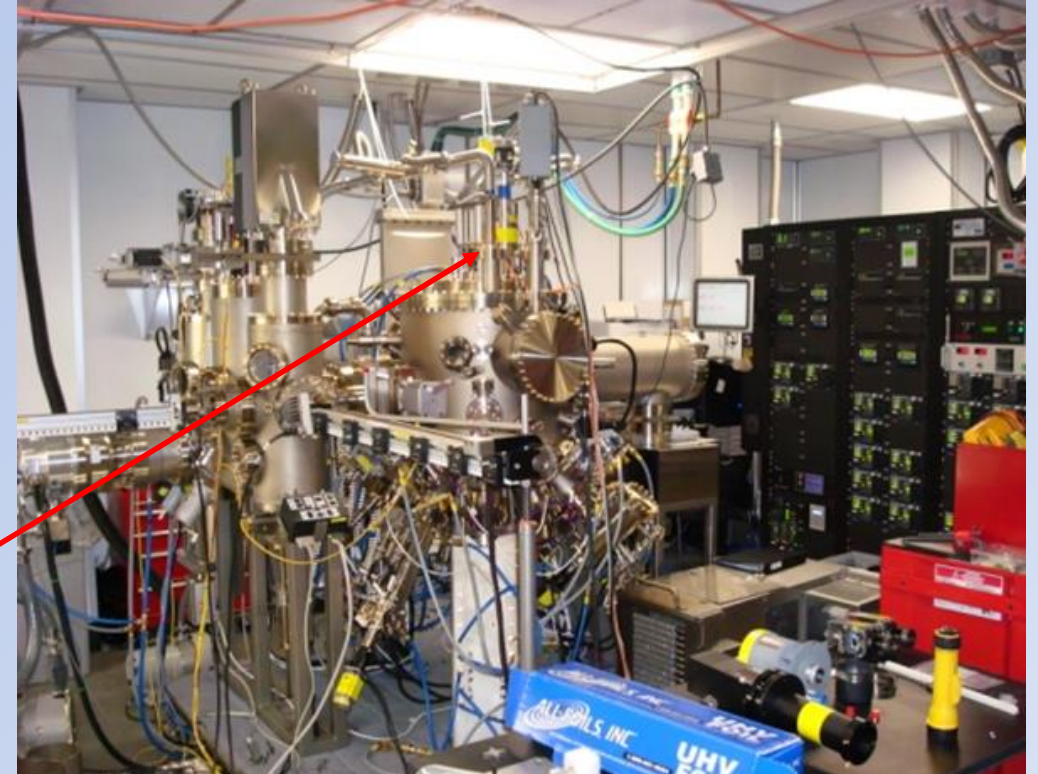
Electronics rack

A quick tour of the MBE facilities at the University of Iowa:

EPI930



GEN20



Liquid nitrogen lines

Closed cycle He cryopump

Group III Knudsen cell and group V cracker cell

Group III K-cell



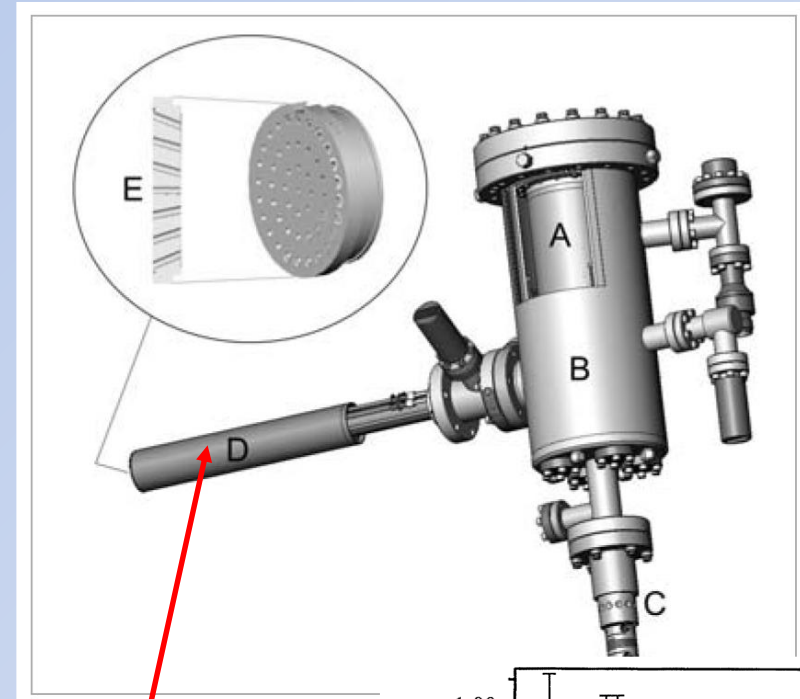
PBN crucible Power feedthrough

$$Flux \propto p_0 \exp(-L_0/RT)$$

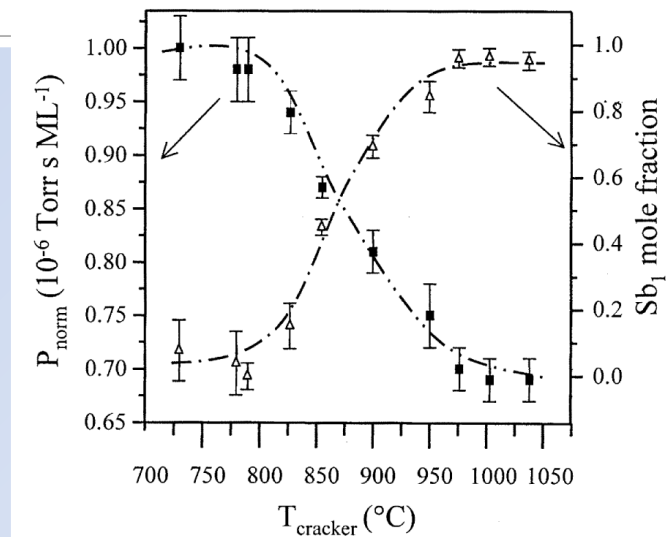
L_0 : latent heat of vaporization
 R: gas constant
 T: temperature

Thermocouple
 feedthroughs

Group V cracker cell



Cracking zone



Where did MBE come from?

- Invented in 1968 by John Arthur (from Iowa State University) and Alfred Cho at Bell Laboratories
 - Arthur: UHV technique for surface science
 - Cho: RHEED and growth of device quality materials
- Built upon principles from materials thermodynamics, metallurgy

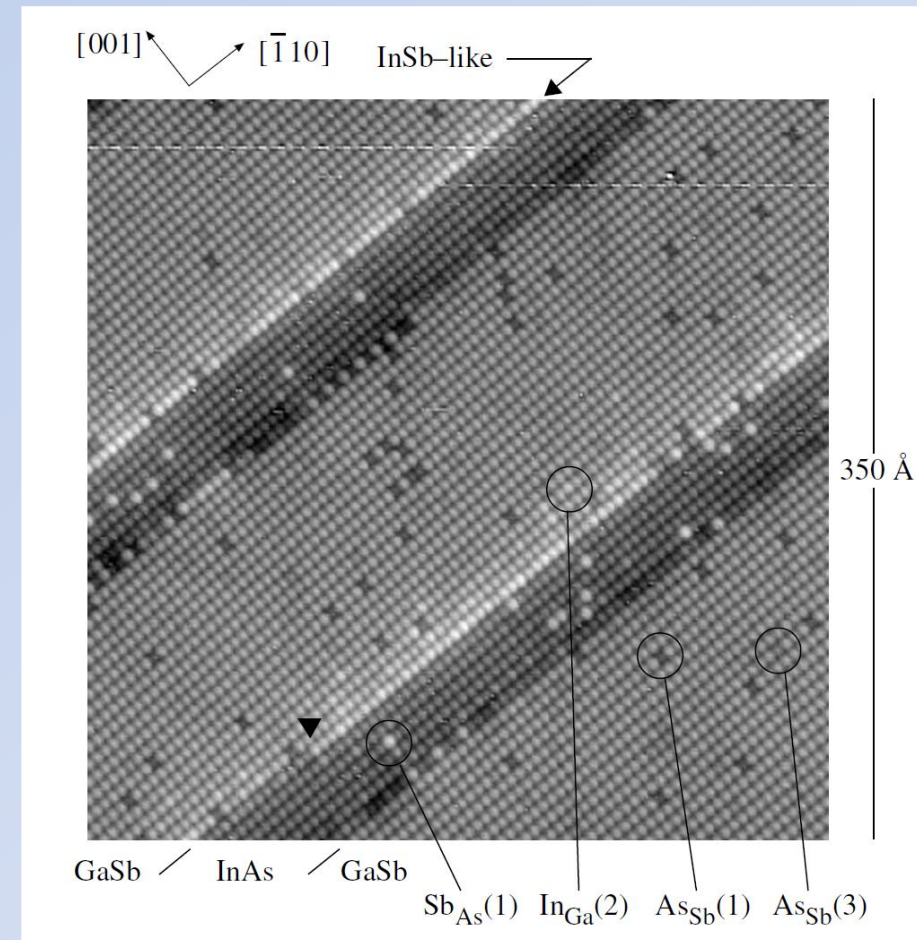
- The Delhi iron pillar was forged in 500 CE from wrought iron, but has never rusted.



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- **Technique has evolved with the invention of powerful vacuum and surface analysis technologies: mass spectrometry (1950's and 60's), RHEED, scanning tunneling microscopy (early 1980's), atomic force microscopy (late 1980's)**

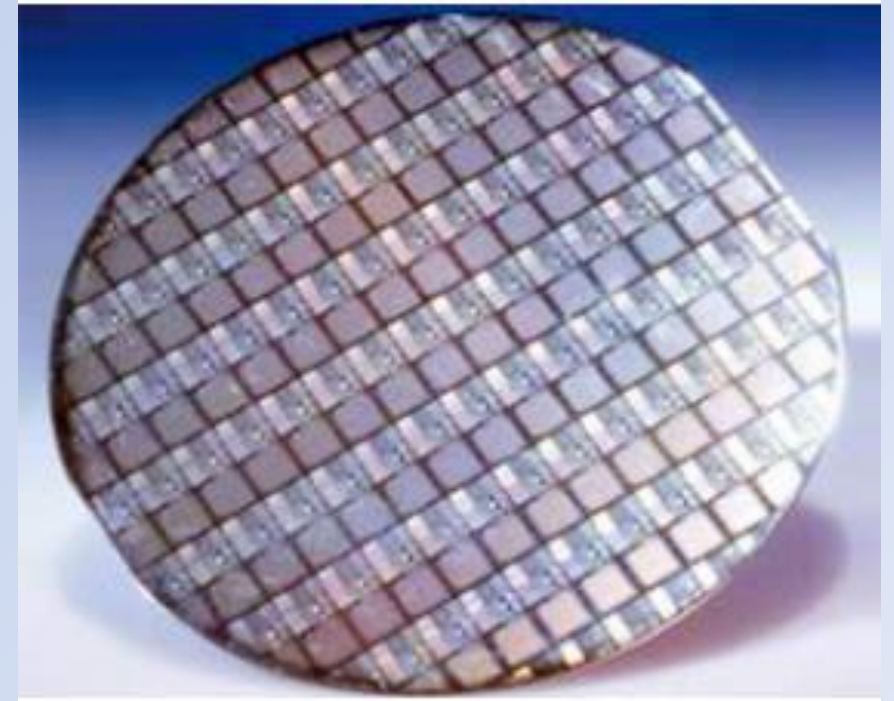
- Scanning tunneling microscope cross section of InAs/GaSb superlattice (Steinshnider et al, PRL 85, 2953 (2000))



Where did MBE come from?

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- **Key technology for research, development, and industrial production of compound semiconductor materials for solid state devices such as laser diodes, light emitting diodes, detectors, solar cells, and transistors**

- GaAs pHEMT wafer

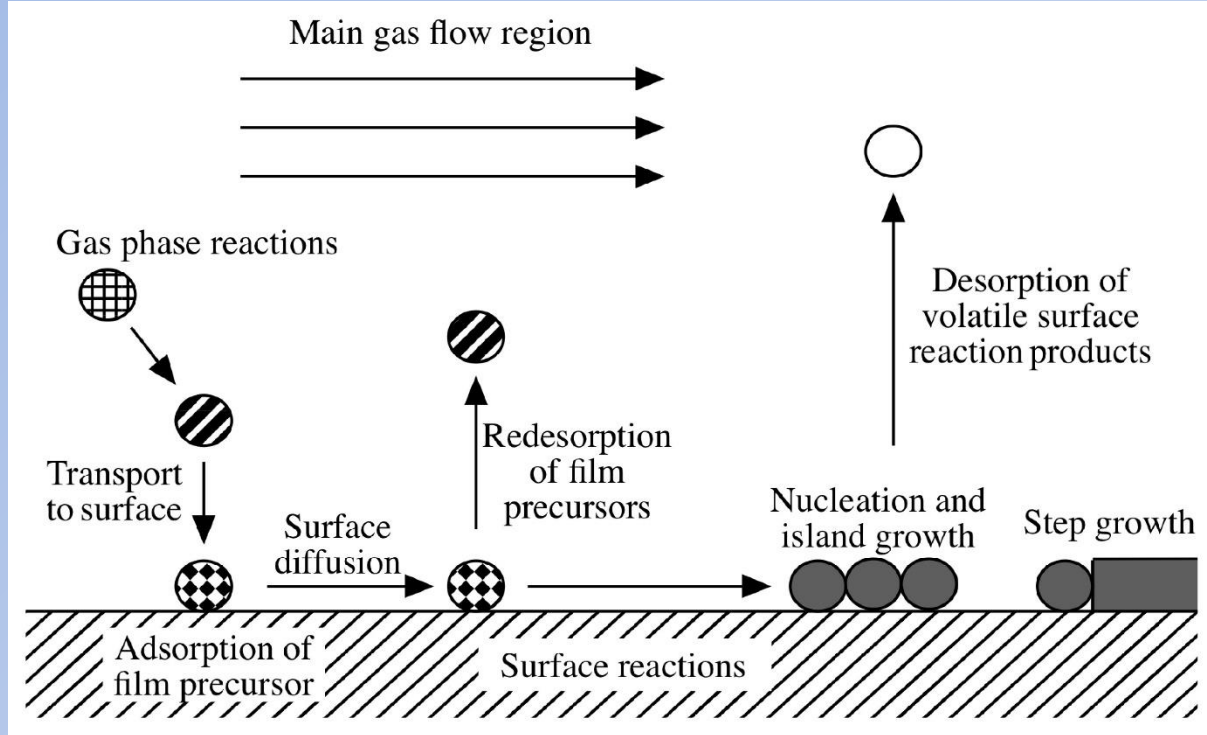


Metal organic vapor phase epitaxy: flexible, high throughput technique

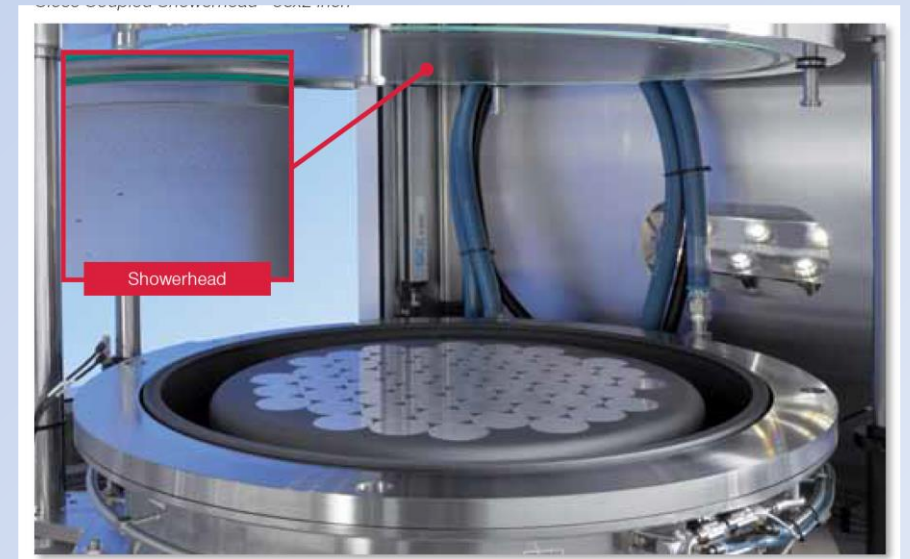
Source gases:

$\text{Ga}(\text{CH}_3)_3$
 $\text{In}(\text{CH}_3)_3$
 $\text{Al}(\text{CH}_3)_3$

SiH_3
 AsH_3
 PH_3
 NH_3



- Metal + precursor gas carried to substrate
- Moderate growth rates (1-10 $\mu\text{m/hr}$)
- Good uniformity, high throughput
- Thin layers, but less abrupt interfaces
- In-situ monitoring harder (high pressure)
- Toxic gases
- Higher growth temperatures
- Dominant technology for solid state lighting



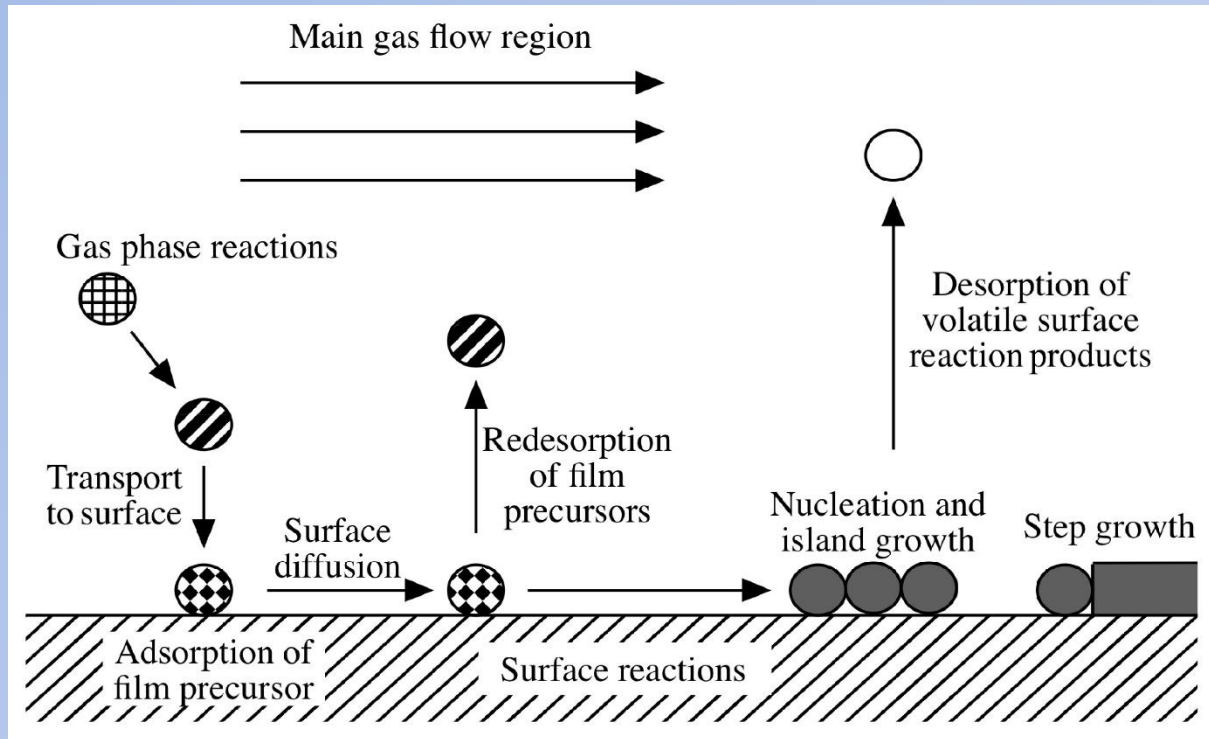
55x2" showerhead growth chamber

Metal organic vapor phase epitaxy: flexible, high throughput technique

Source gases:

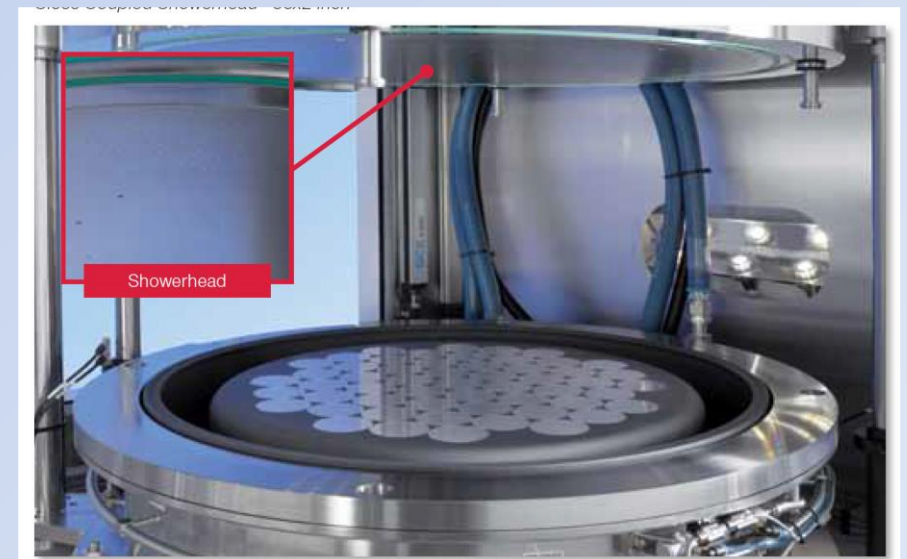
$\text{Ga}(\text{CH}_3)_3$
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- MBE is a more flexible technique used prominently in research, for growth of materials with very thin layers with abrupt interfaces, and for better per wafer layer uniformity.



55x2" showerhead growth chamber

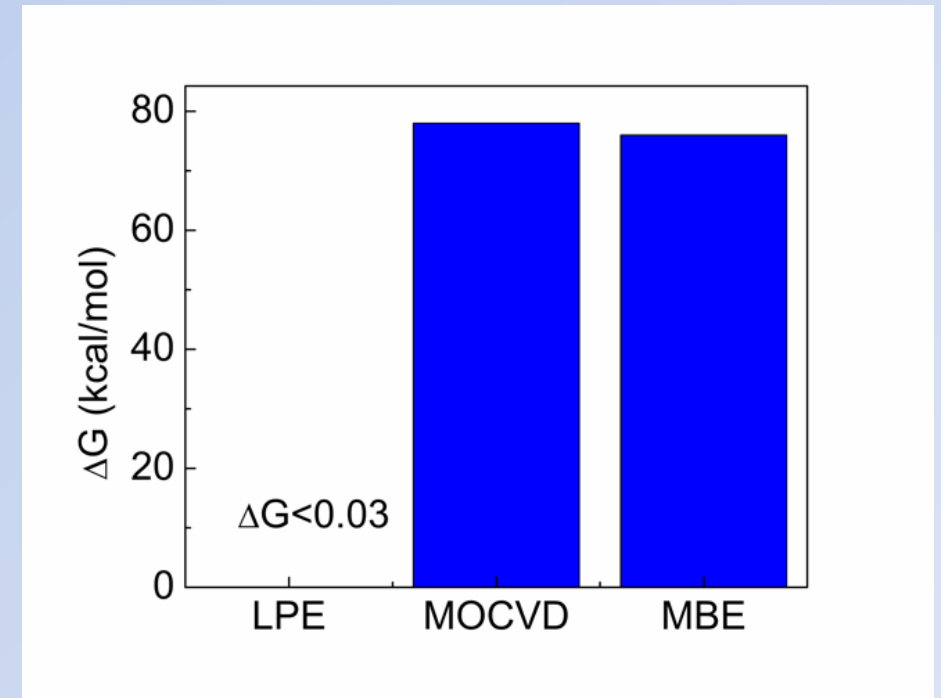
MBE is considered to be a nonequilibrium growth technique, similar to metal organic vapor phase epitaxy (MOVPE) but unlike liquid phase epitaxy due to large driving force for crystal growth

Driving force for epitaxy:

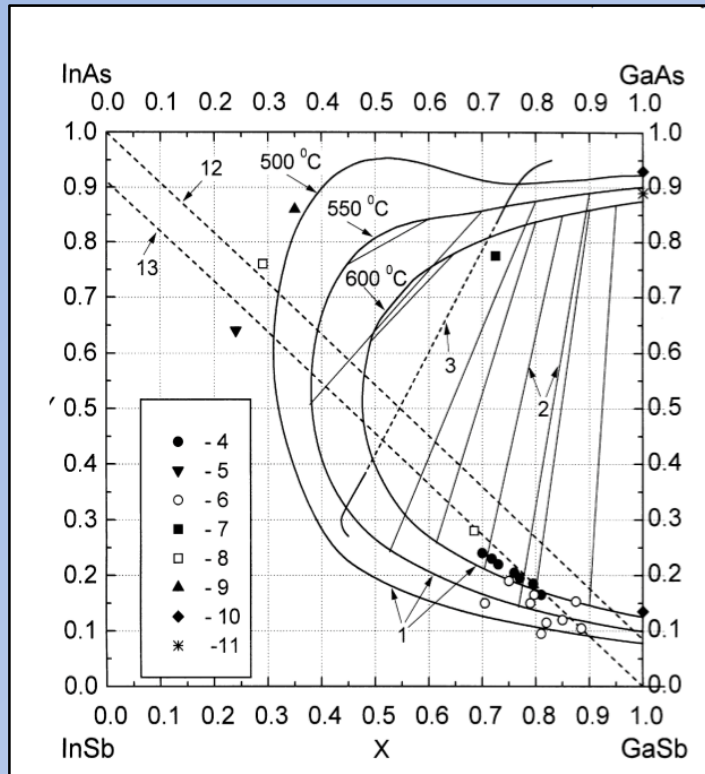
$$\Delta\mu_{driving} = \mu_{products} - \mu_{sources}$$

- μ is the chemical potential
- Sources are molecular beams from the K-cells
- Products are the crystal layers that form on the substrate

Growth phase determined by surface thermodynamics rather than by bulk thermodynamics

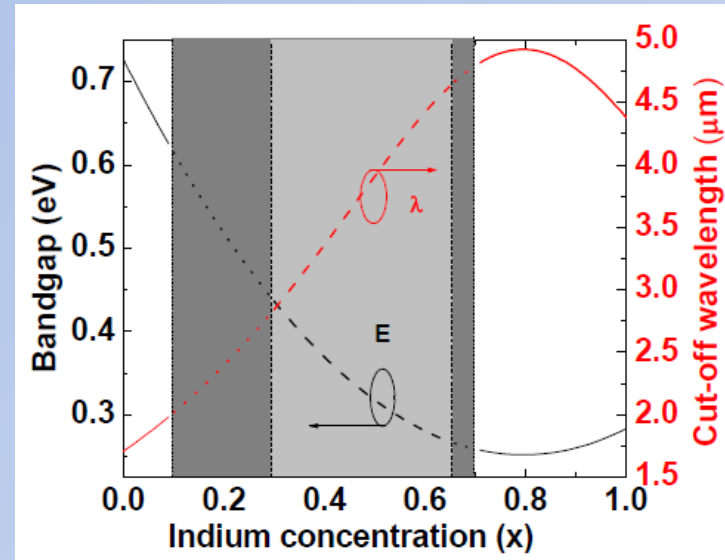
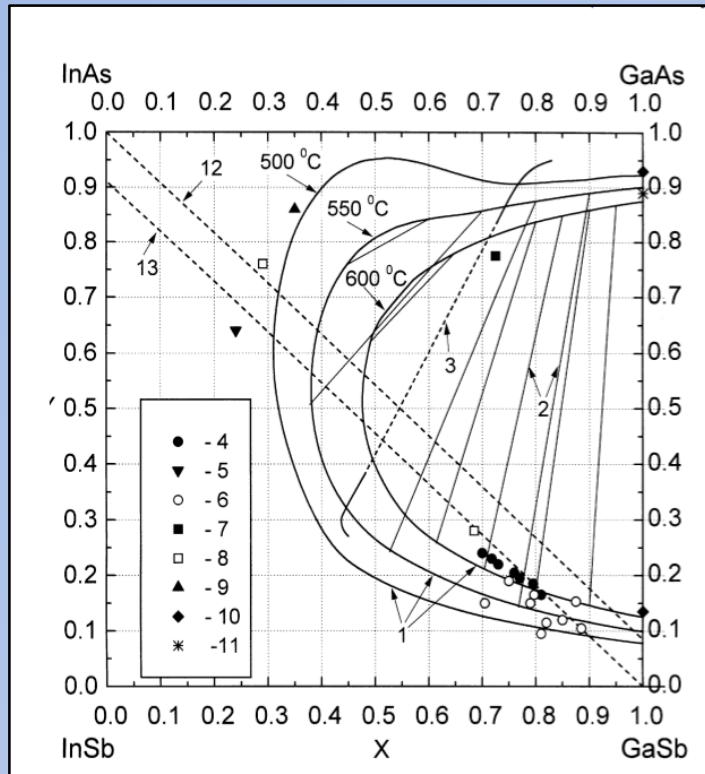


MBE can be used to grow thermodynamically unstable alloys



- Binodal isotherms (1) for GaInAsSb.

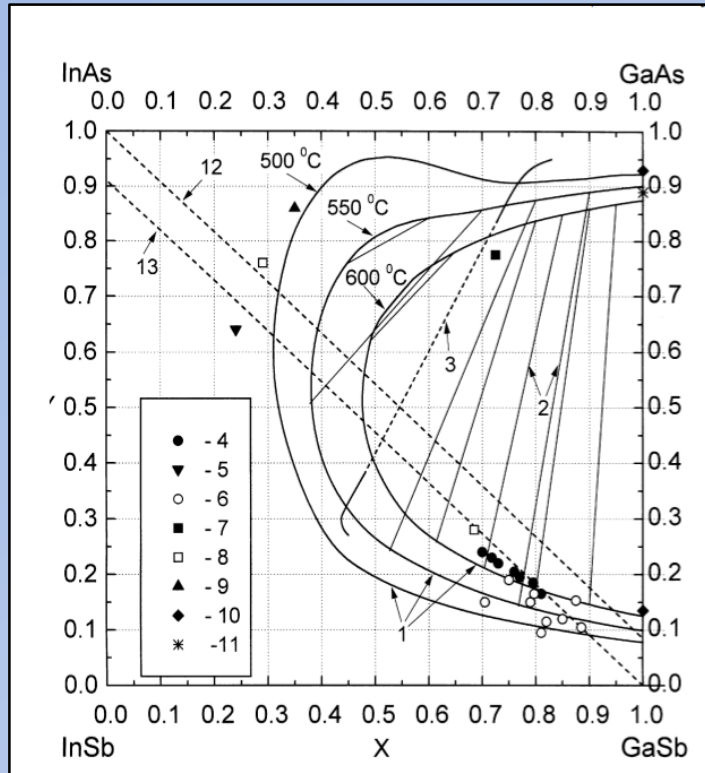
MBE can be used to grow thermodynamically unstable alloys



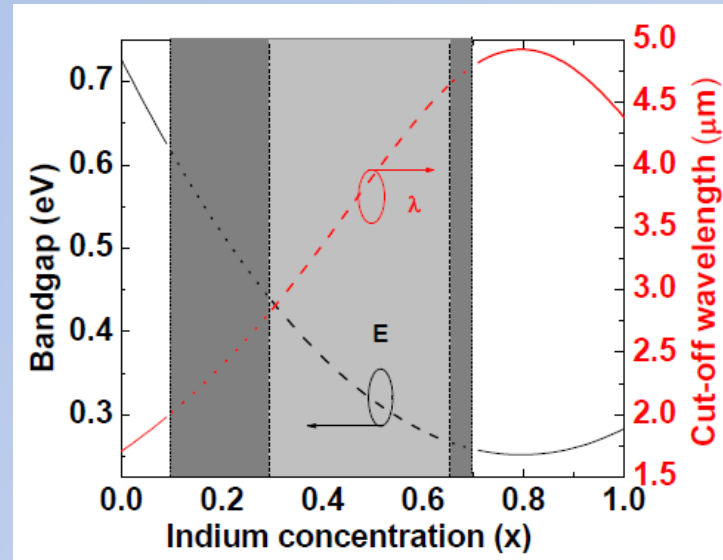
- $\text{Ga}(1-x)\text{In}(x)\text{As}(y)\text{Sb}(1-y)$ lattice-matched to GaSb for growth at 500 C
- Stable alloy (white), metastable (dark grey), stable (light grey)

- Binodal isotherms (1) for GaInAsSb.

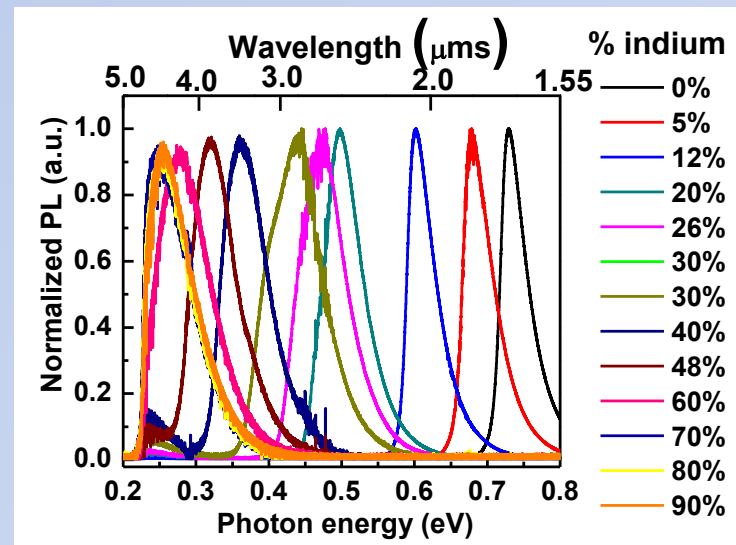
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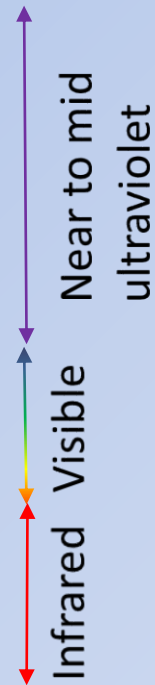
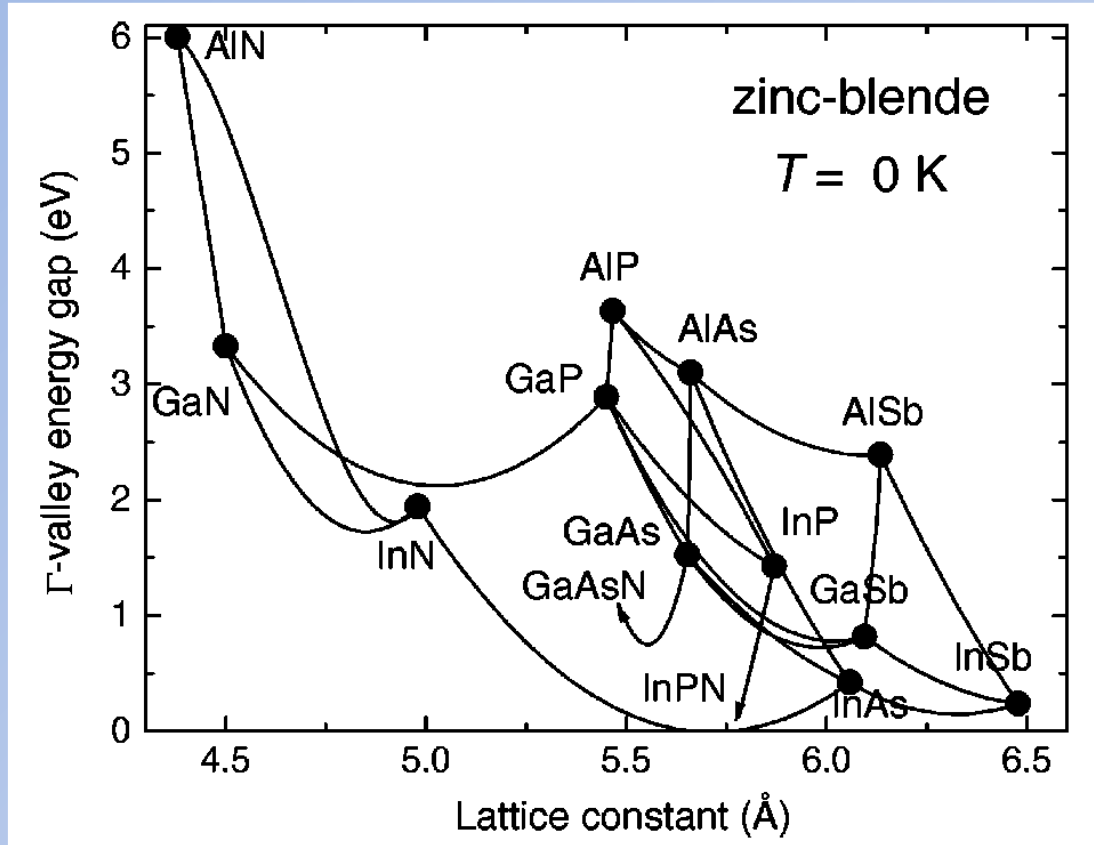
- Ga(1-x)In(x)As(y)Sb(1-y) lattice-matched to GaSb for growth at 500 C
- Stable alloy (white), metastable (dark grey), stable (light grey)



- We used MBE to grow high quality alloys across the compositional range at 400-450 C
- Room temperature photoluminescence across compositional range

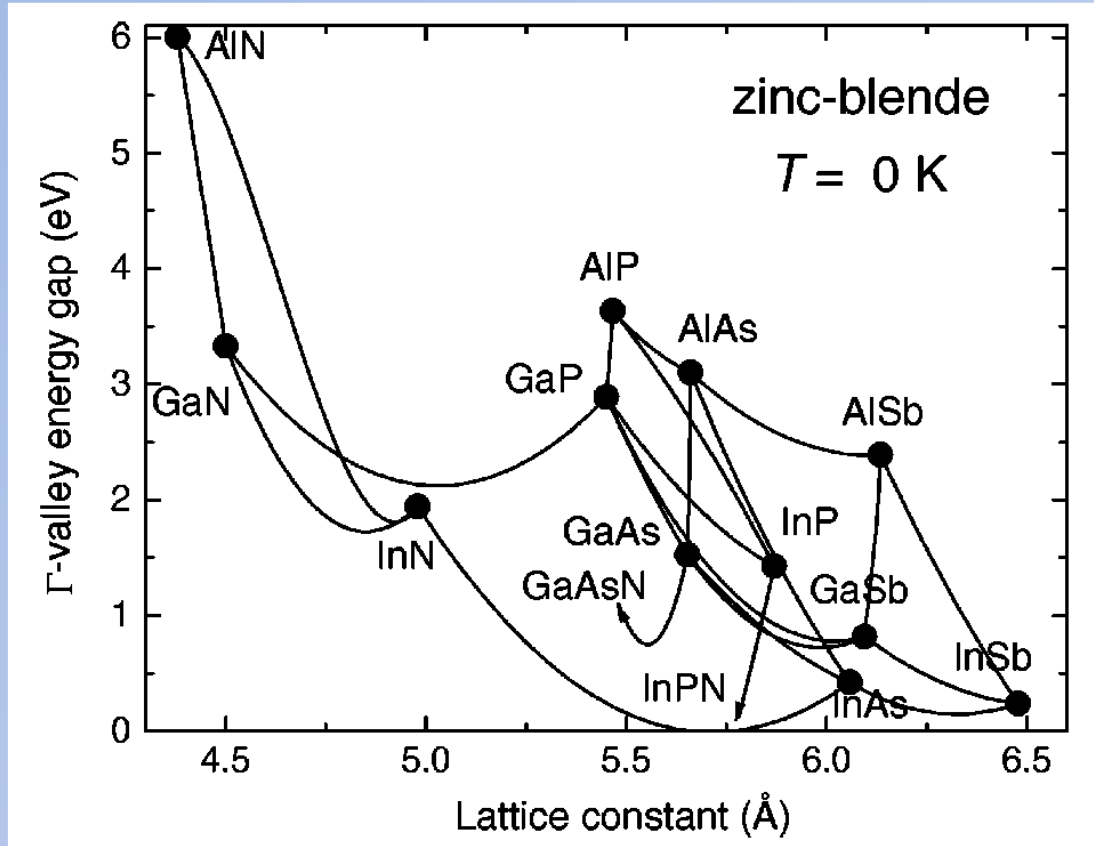
Epitaxial growth unleashed an explosion of materials research and engineering that vigorously continues to this day

Group III-V compound semiconductors have very good optical properties compared to e.g. group IV

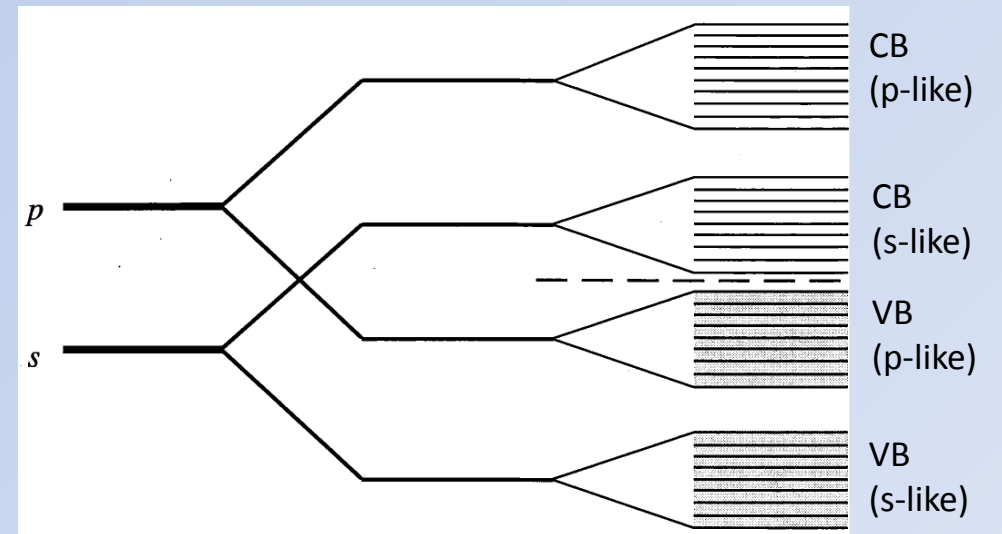


	II	III	IV	V	VI
		5 B 10.811	6 C 12.0107	7 N 14.0067	8 O 15.9994
		13 Al 26.9815	14 Si 28.0855	15 P 30.9738	16 S 32.065
30	Zn 65.38	31 Ga 69.723	32 Ge 72.63	33 As 74.9216	34 Se 78.96
48	Cd 112.411	49 In 114.818	50 Sn 118.71	51 Sb 121.76	52 Te 127.6
80	Hg 200.59	81 Tl 204.383	82 Pb 207.2	83 Bi 208.98	84 Po [210]

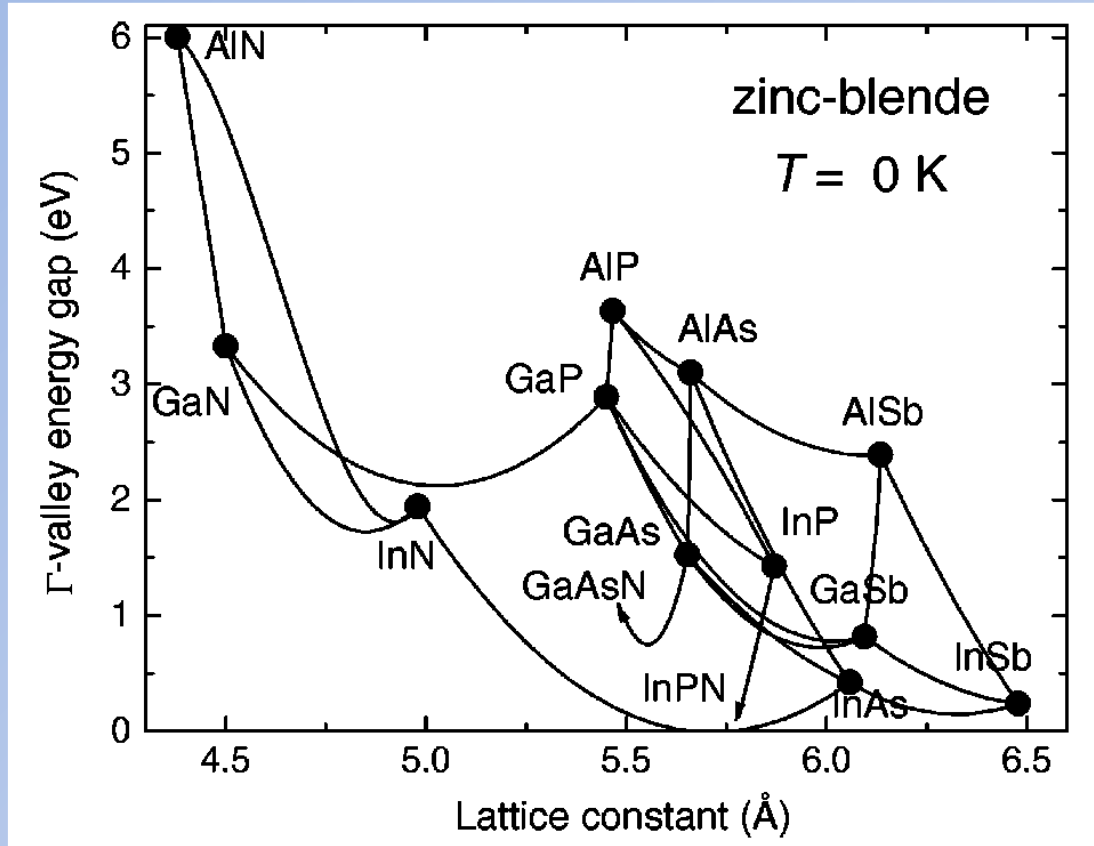
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Discrete molecular energy levels broaden into energy bands in crystalline solid

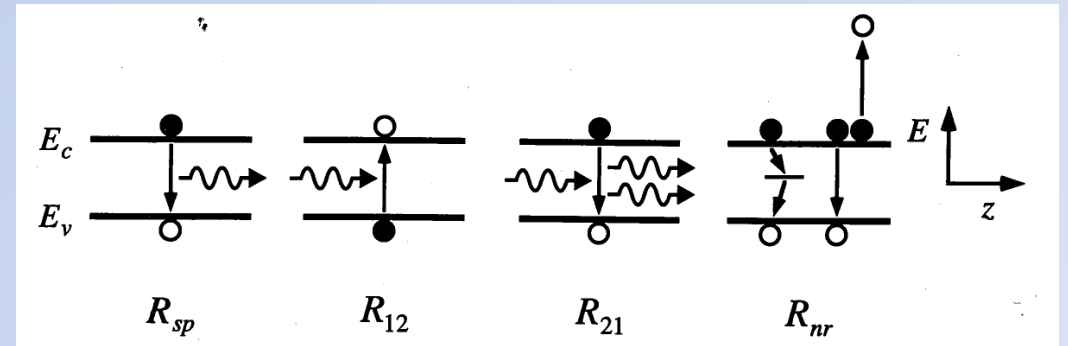


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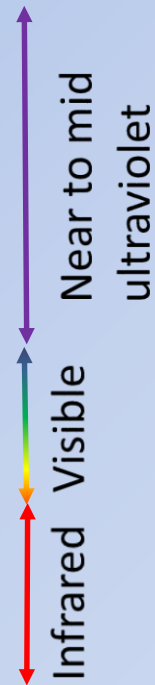
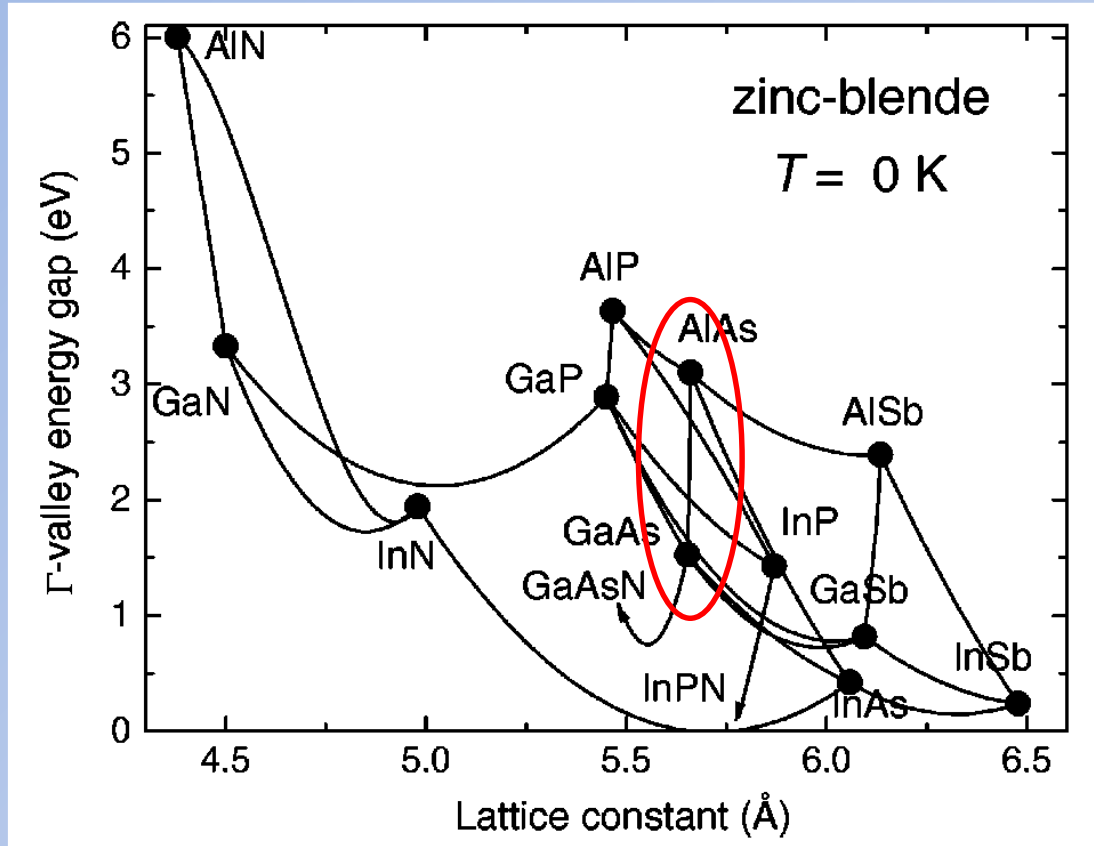
↑ Near to mid ultraviolet
↑ Visible
↑ Infrared

- Transitions of electronic carriers between bands can generate light (radiative) or heat (nonradiative)
- Energy gaps in binary semiconductors span the infrared through the mid-ultraviolet.



Epitaxial growth unleashed an explosion of materials research and engineering that vigorously continues to this day

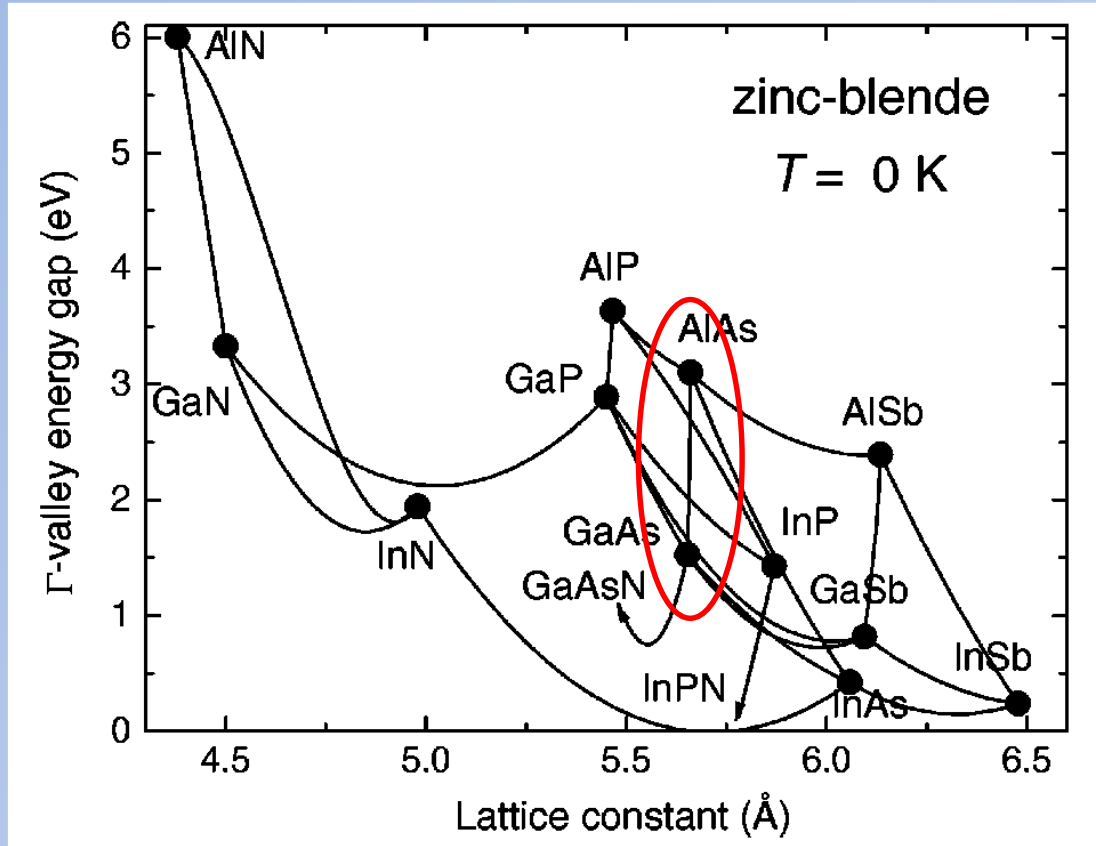
Initially, materials with nearly the same lattice constant such as GaAs/Al(Ga)As stacked together in a layered heterostructure.



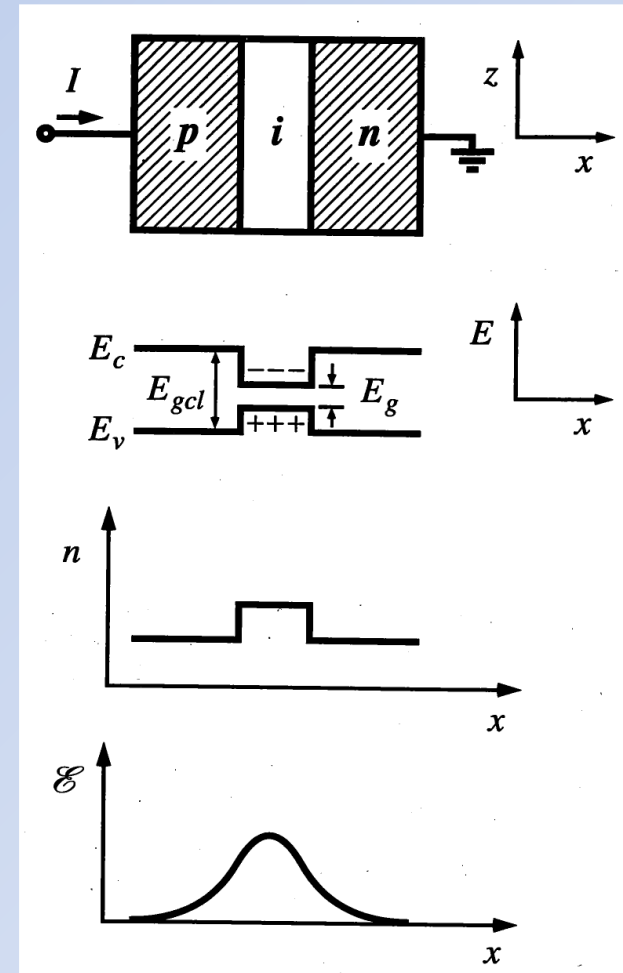
5.65 Å materials (GaAs substrate)

Epitaxial growth unleashed an explosion of materials research and engineering that vigorously continues to this day

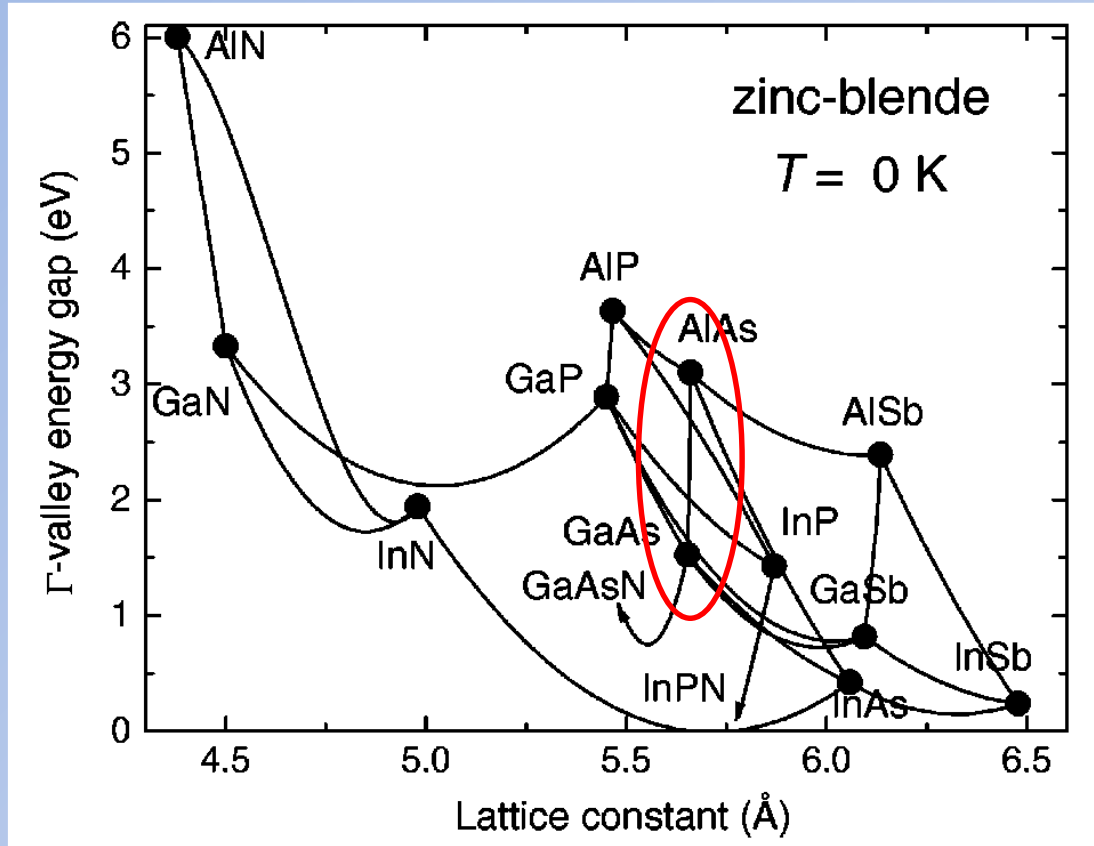
First room temperature laser (1970) a GaAs/AlGaAs double heterostructure grown by liquid phase epitaxy



5.65 \AA materials (GaAs substrate)



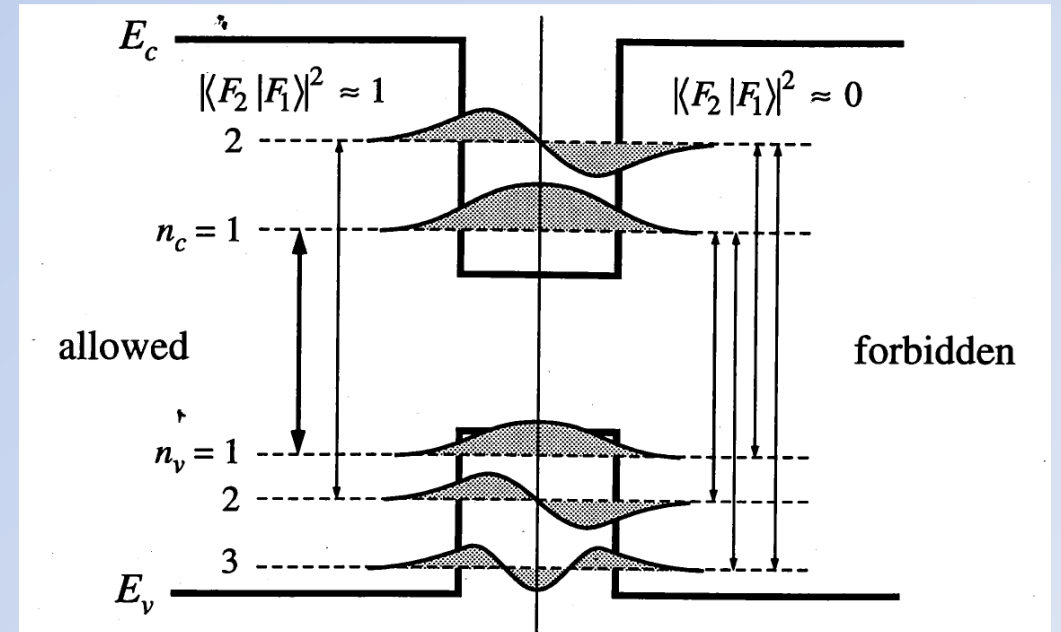
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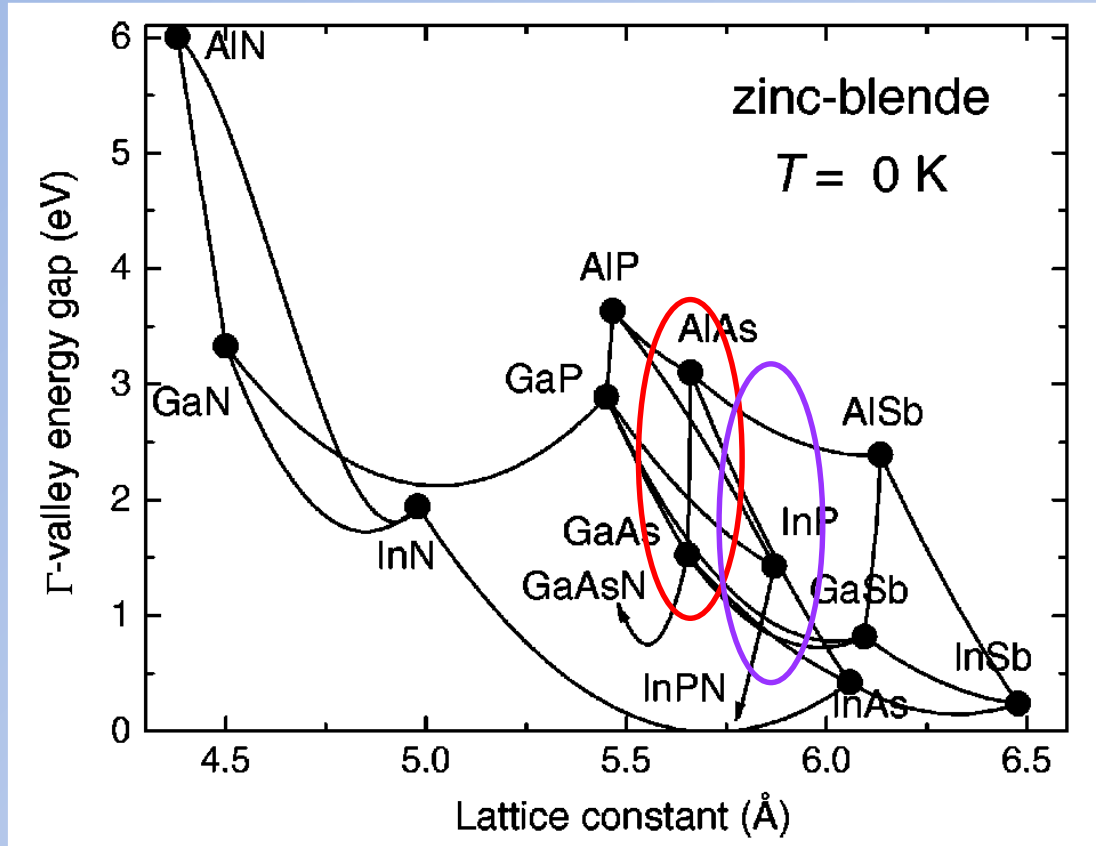
5.65 Å materials (GaAs substrate)

By making layers thin compared to the electron de Broglie wavelength (~30-40 nm GaAs), quantum wells can be created

Infrared Visible Near to mid ultraviolet



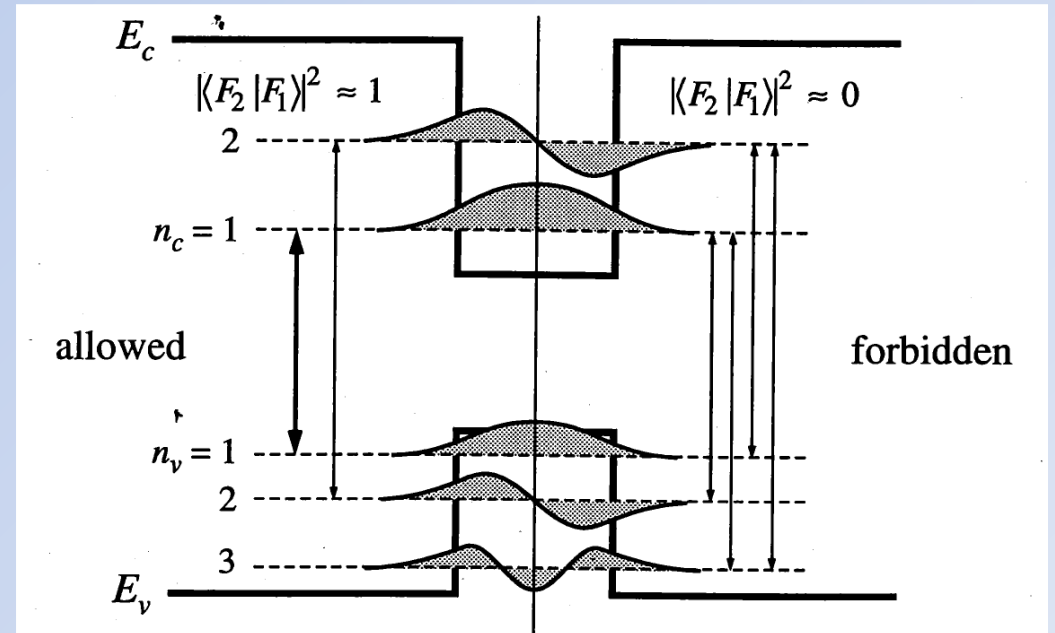
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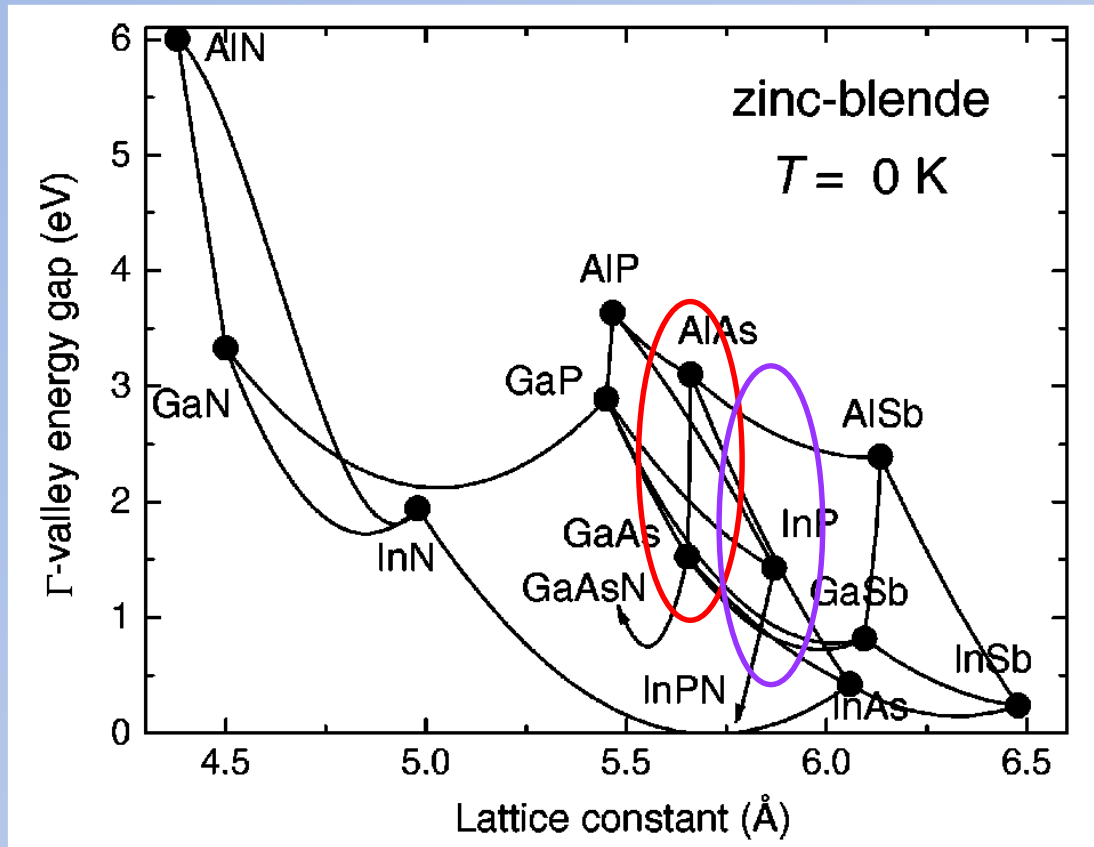
5.65 Å materials (GaAs substrate)
5.87 Å materials (InP substrate)

GaInAsSb/InP QWs on InP substrates as well as GaAs/AlAs QWs on GaAs important for infrared laser diodes and light emitting diodes for telecom at 0.8, 1.3 and 1.55 μm

↑ Near to mid ultraviolet
↓ Visible
↓ Infrared



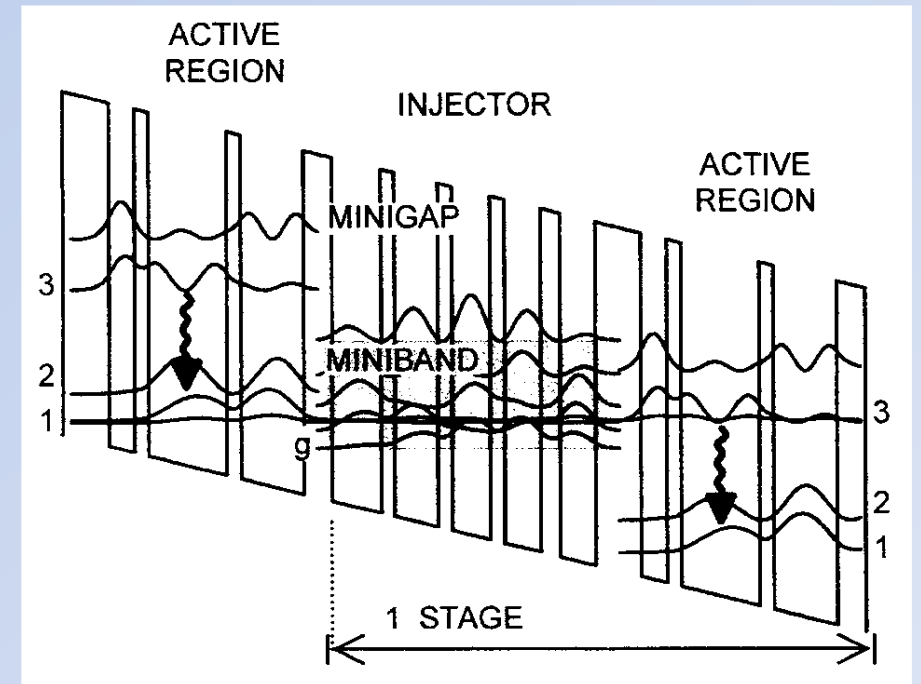
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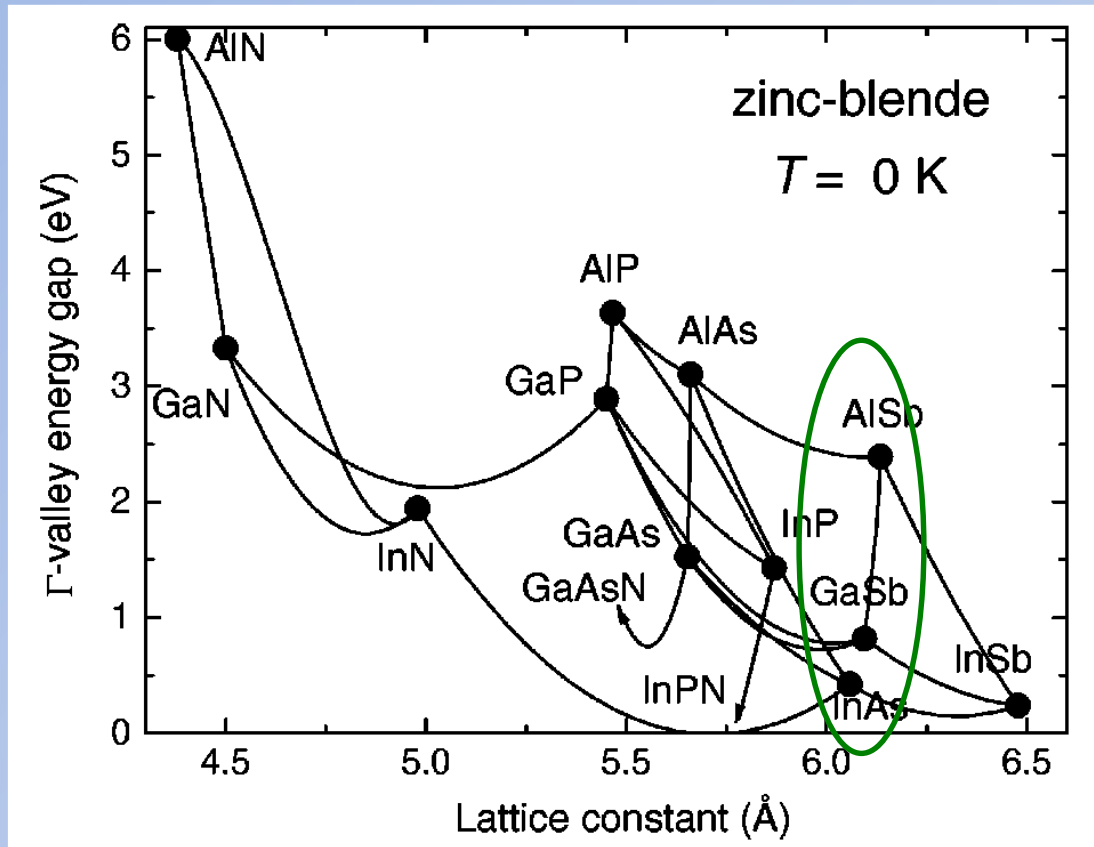
5.65 Å materials (GaAs substrate)
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Infrared Visible Near to mid ultraviolet

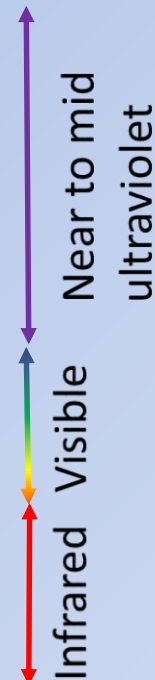
Electronic coupling of quantum wells from the same materials, and using intersubband transitions led to quantum cascade lasers emitting from the mid to far infrared, 4 μm to >100 μm (0.3 eV to 0.012 eV)



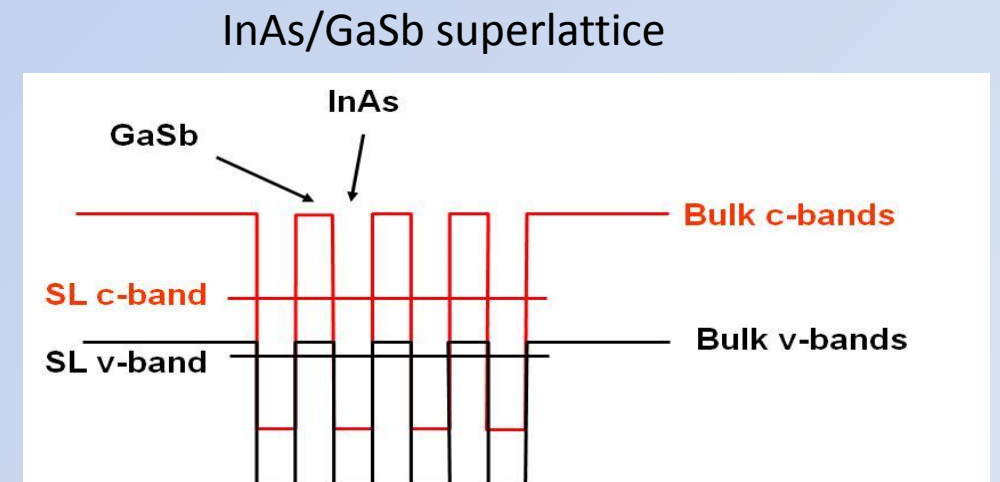
Epitaxial growth unleashed an explosion of materials research and engineering that vigorously continues to this day



6.1 Å materials (GaSb substrate)

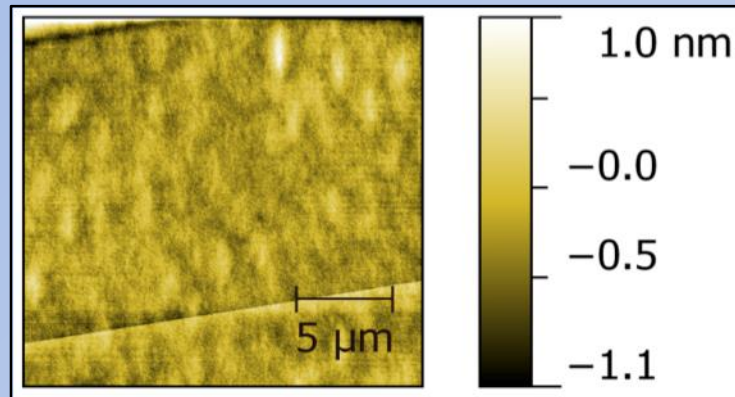


The 6.1 Å materials are a flexible system of narrow gap semiconductors for producing mid- and long-wave optoelectronics.

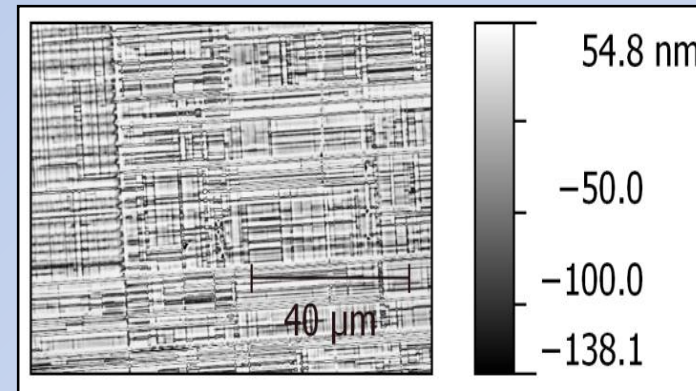


Materials combinations can be vastly increased through pseudomorphic growth

- Pseudomorphic growth: coherently strained mismatched materials
 - Thickness \times strain \sim constant



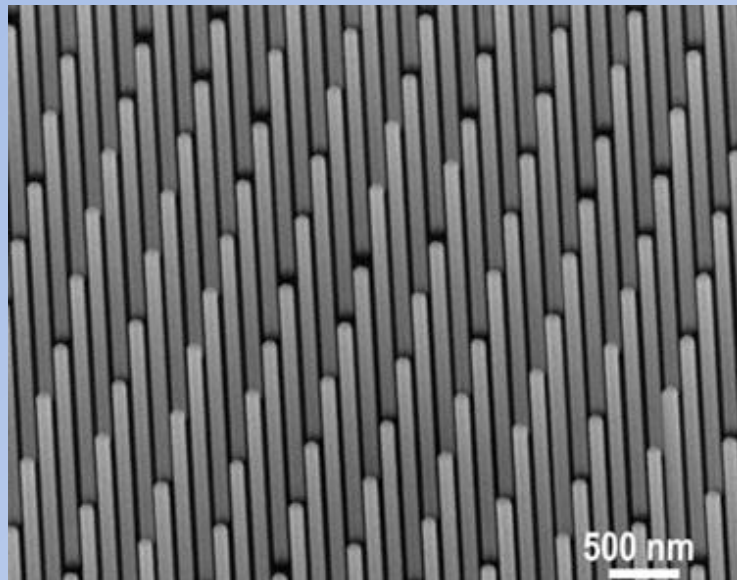
Weakly relaxed



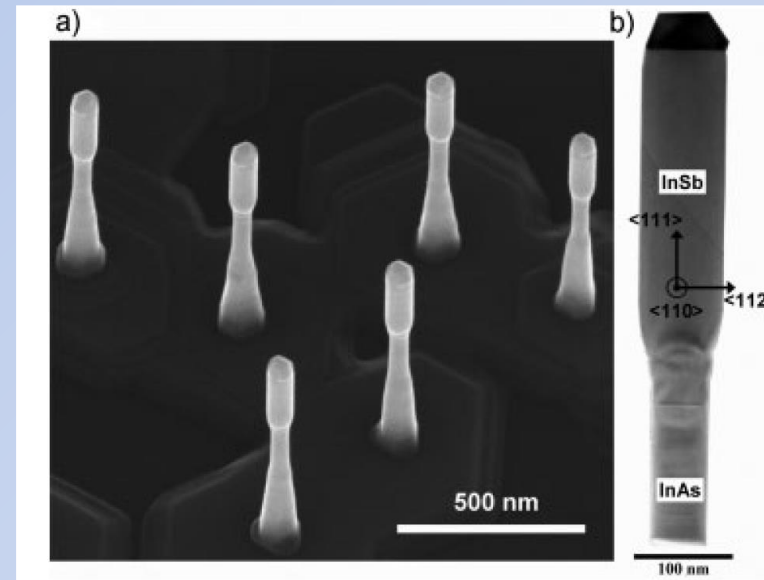
Strongly relaxed

Materials combinations can be greatly increased through pseudomorphic growth

GaAs nanowires on Si¹



InSb / InAs segmented nanowires²

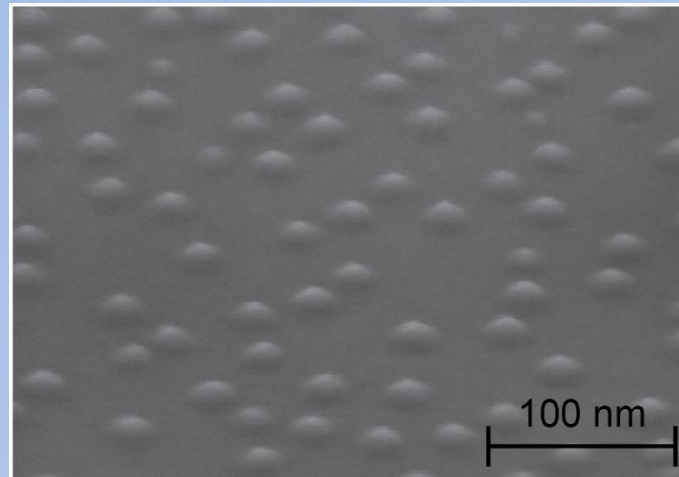


¹Tomioka et al, *Nanotechnology* **20**, 145302 (2009)

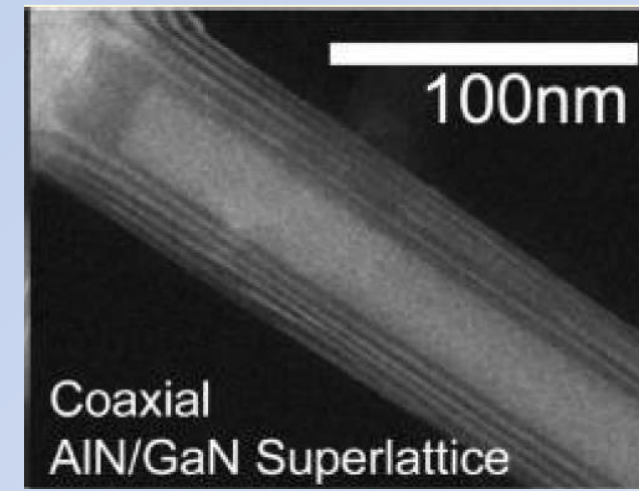
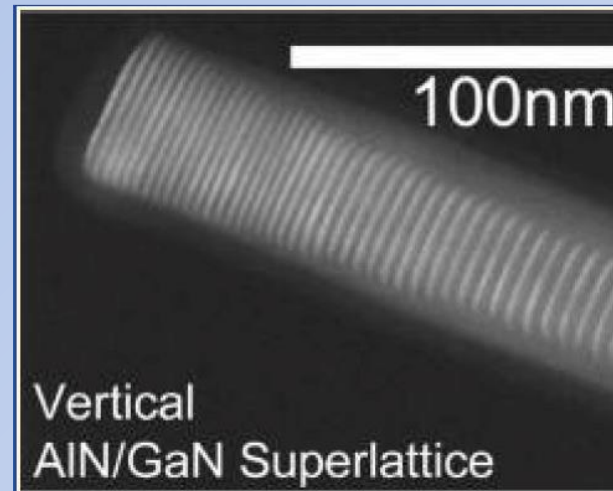
²Caroff et al, *Small* **4**(7), 878–882 (2008)

Materials combinations can be greatly increased through pseudomorphic growth

InAs quantum dots on GaAs²



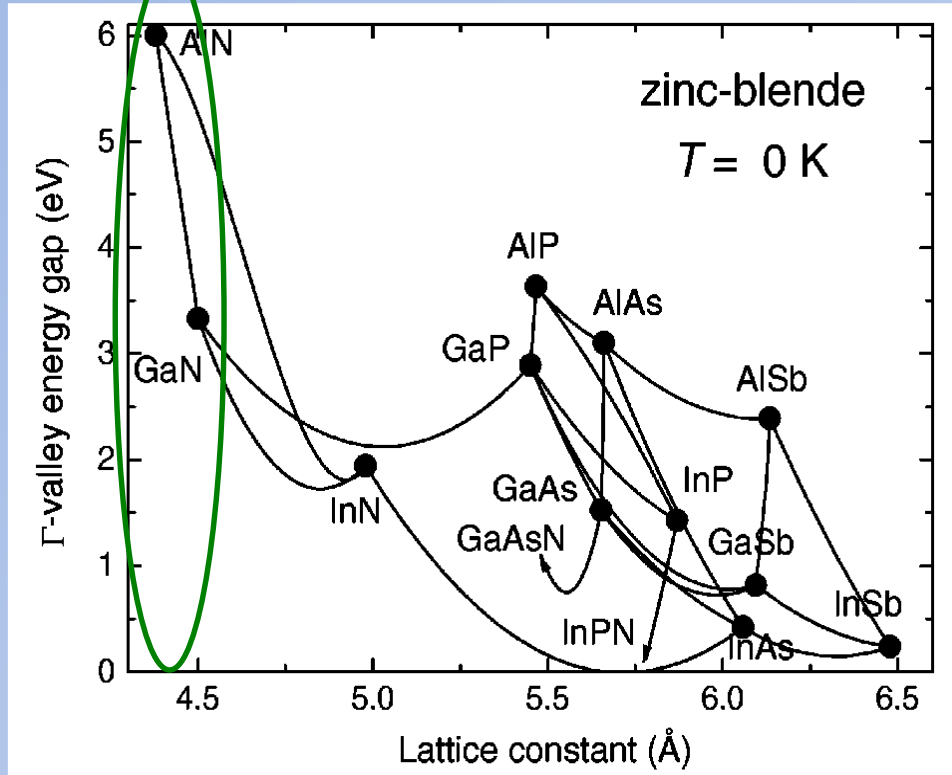
Axial layering and core shell nanowires²



²W. Stumpf, <http://www.mbe.ethz.ch/index.php?id=mbe>

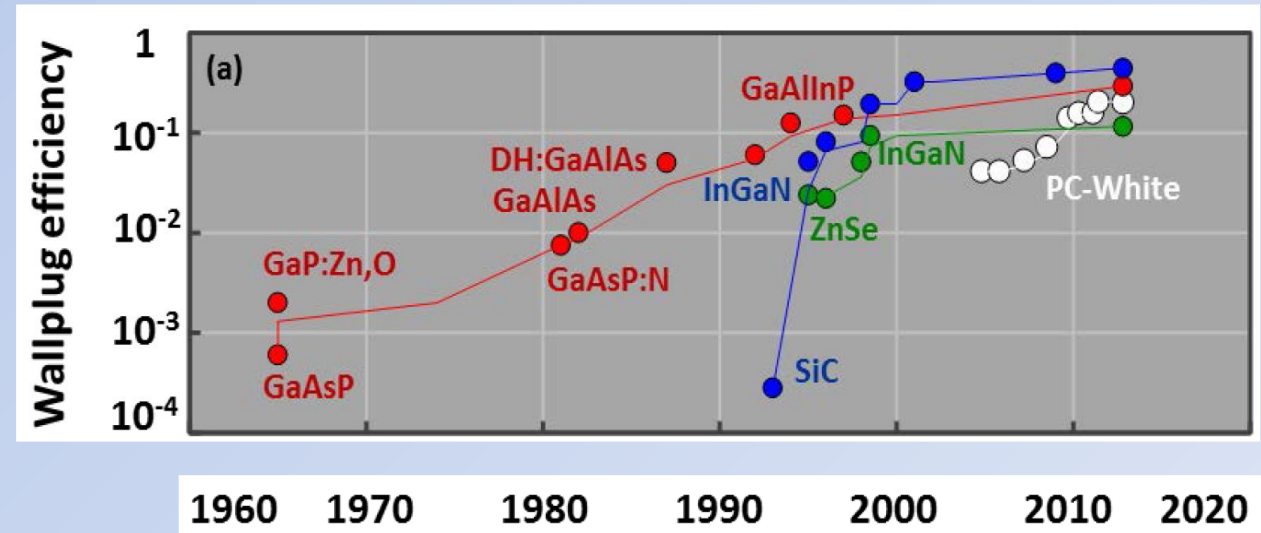
²Carnevale et al., *Nano Lett.* **211**, 866–871 (2011)

GaN was grown very early on (1960's) along with other binary semiconductors. Why did it take 30-40 years to see bright commercial blue leds and laser diodes?



6.1 Å materials (GaSb substrate)

History of red/green/blue LEDs



GaN was grown very early on (1960's) along with other binary semiconductors. Why did it take 30-40 years to see bright commercial blue leds and laser diodes?

- Nitrogen is typically gaseous N_2 , so liquid phase epitaxy could not be used.
- Initially grown by HVPE, but had to await development of MOVPE and MBE for higher quality films

II	III	IV	V	VI
	5 B 10.811	6 C 12.0107	7 N 14.0067	8 O 15.9994
	13 Al 26.9815	14 Si 28.0855	15 P 30.9738	16 S 32.065
30 Zn 65.38	31 Ga 69.723	32 Ge 72.63	33 As 74.9216	34 Se 78.96
48 Cd 112.411	49 In 114.818	50 Sn 118.71	51 Sb 121.76	52 Te 127.6
80 Hg 200.59	81 Tl 204.383	82 Pb 207.2	83 Bi 208.98	84 Po [210]

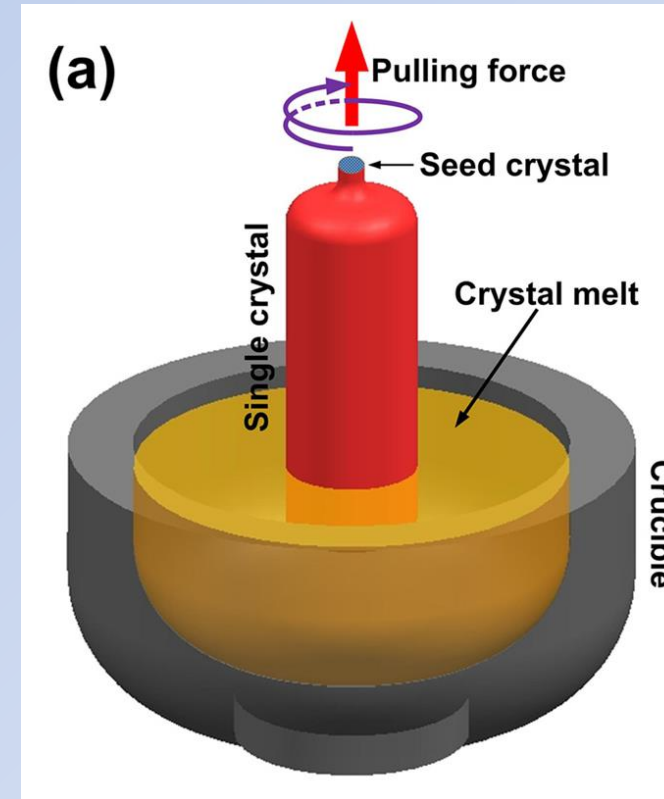
Gaseous N_2
under typical
conditions

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- **Metamorphic growth is** required on foreign substrates, typically sapphire (~15% lattice mismatch)
- Substrates like GaAs, GaP, GaSb cut from boules grown from melts; nitrogen is typically a gas

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Gaseous N₂
under typical
conditions




Czochralski schematic

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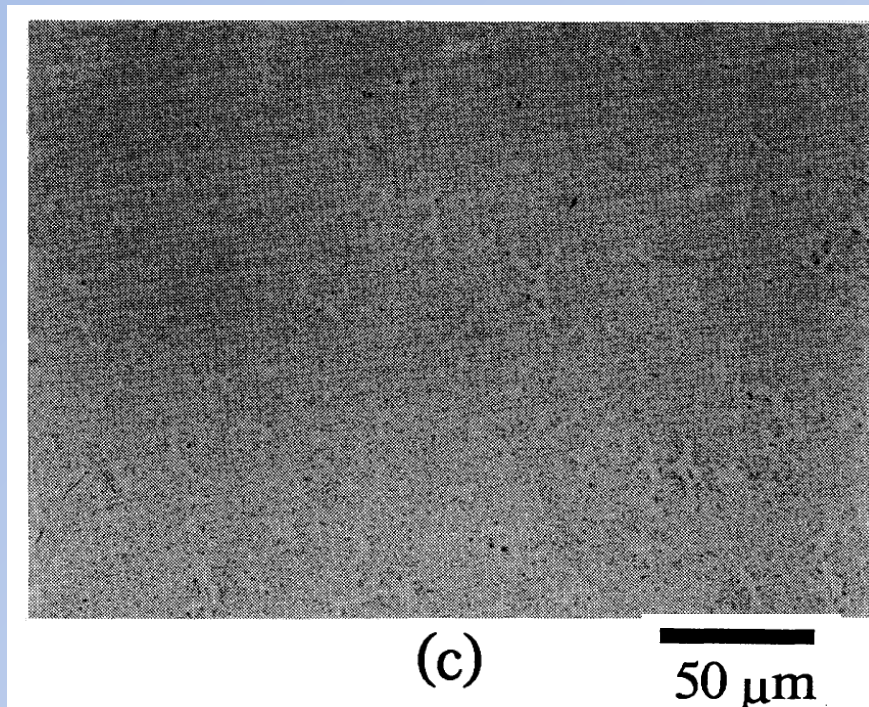
- MOVPE and MBE metamorphic layers on sapphire had high dislocation density and poor quality early on



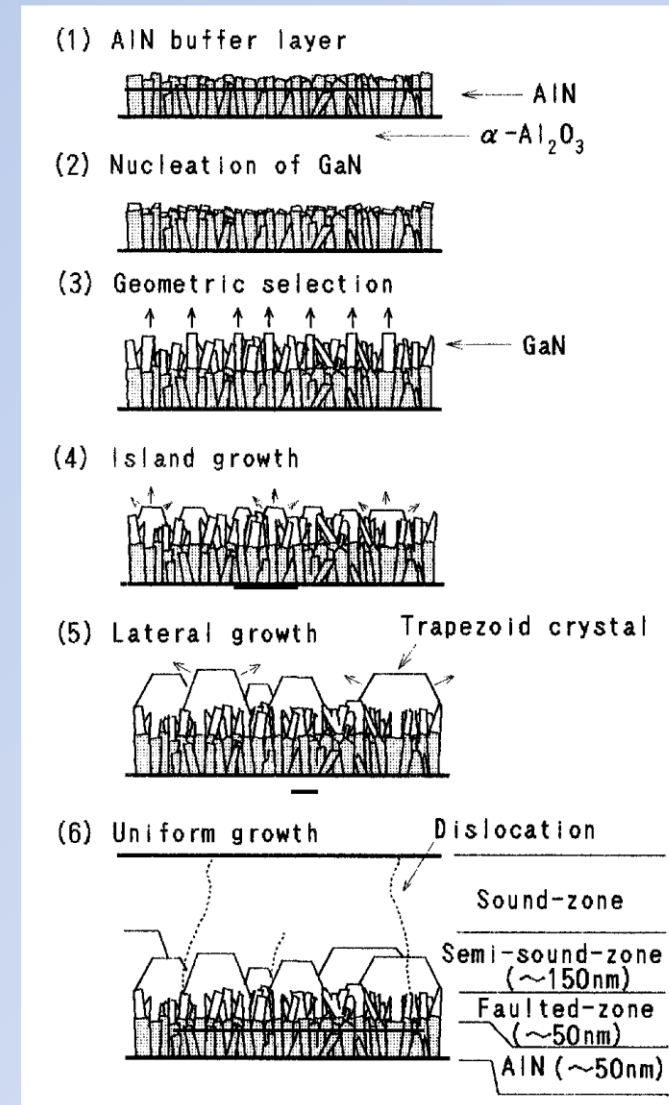
(d)  50 μm

GaN was grown very early on (1960's) along with other binary semiconductors. Why did it take 30-40 years to see bright commercial blue leds and laser diodes?

- Key advance (1983-91) was development of low-temperature-grown GaN and AlN buffer layers between sapphire and GaN



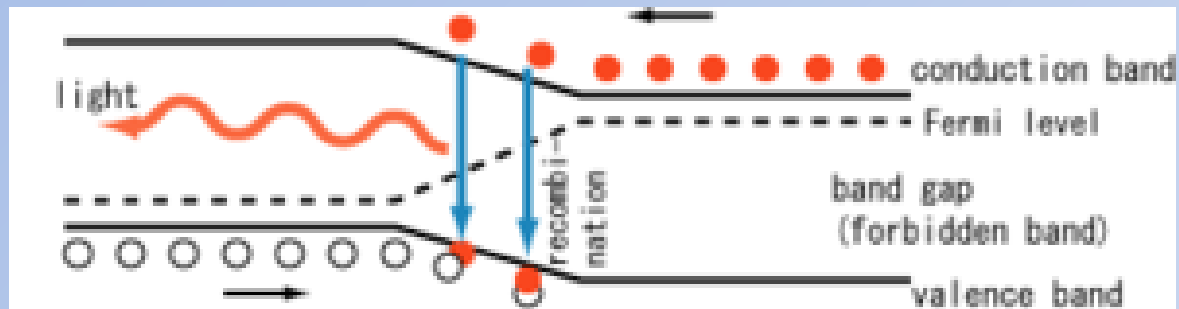
Nakamura, Jap. J. of Appl. Phys **30**, L1705 (1991)



K. Hiramatsu *et al.*, *J. Crystal Growth* **115**, 628 (1991)

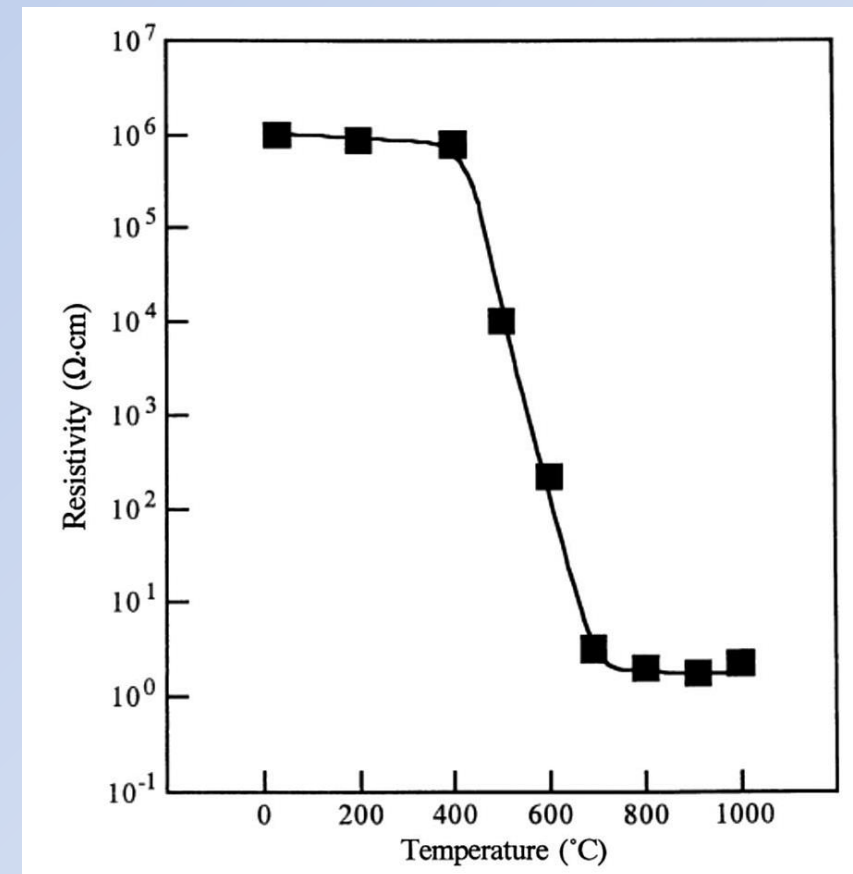
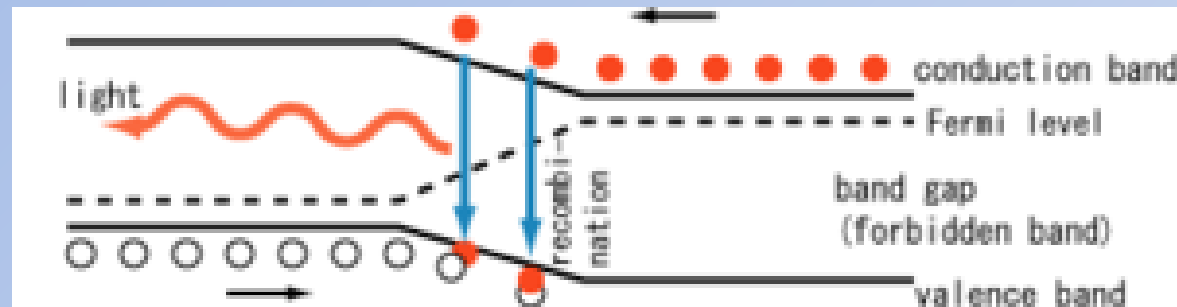
GaN was grown very early on (1960's) along with other binary semiconductors. Why did it take 30-40 years to see bright commercial blue leds and laser diodes?

- LEDs need pn junction
- **Doping problem:** GaN films were consistently n-type and could not be p-doped



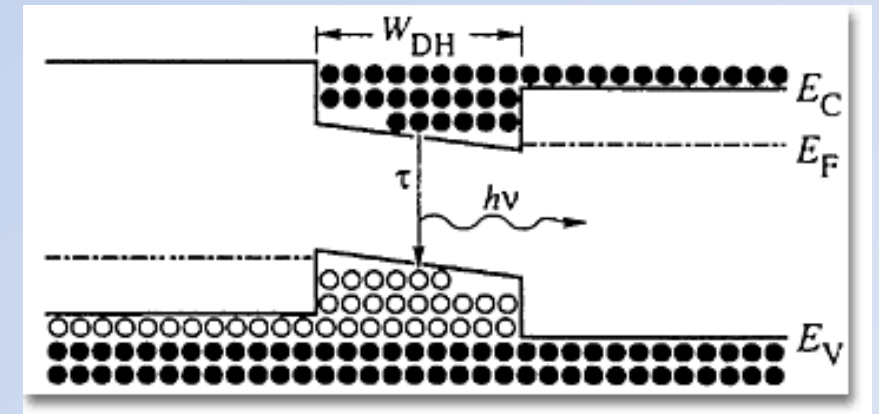
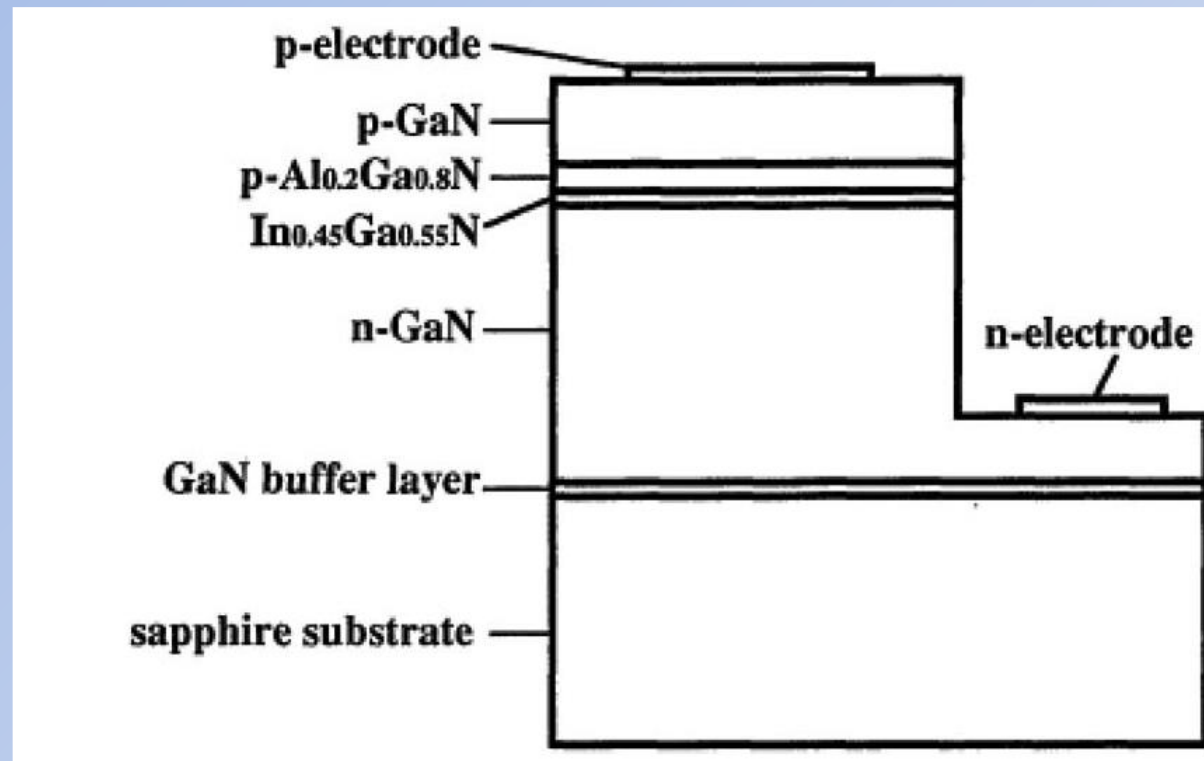
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- Key development: p-dopants (Mg) were being passivated by hydrogen present in the precursor, but could be liberated by a simple post growth anneal in a non-hydrogen atmosphere

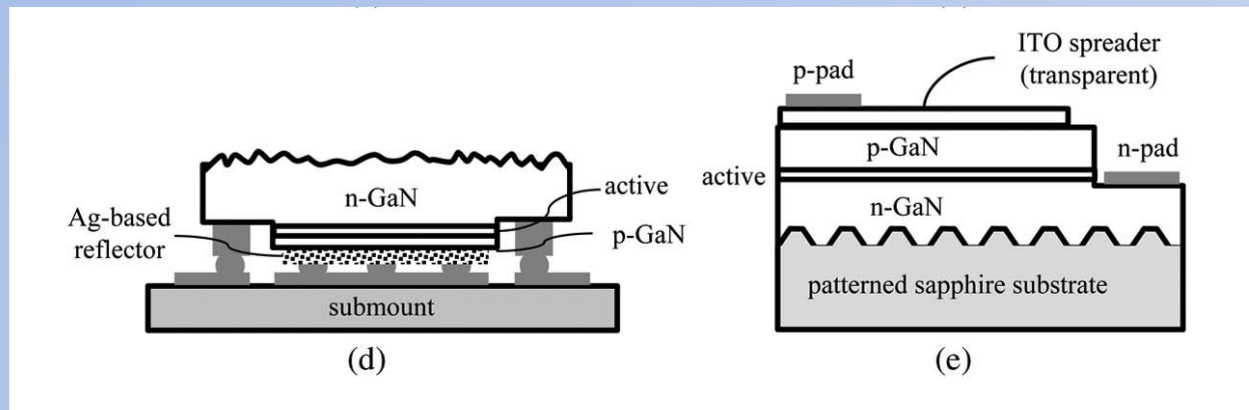


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- Finally, the development of Al(Ga)N and In(Ga)N growth allowed the growth of heterostructures, key for high performance LEDs



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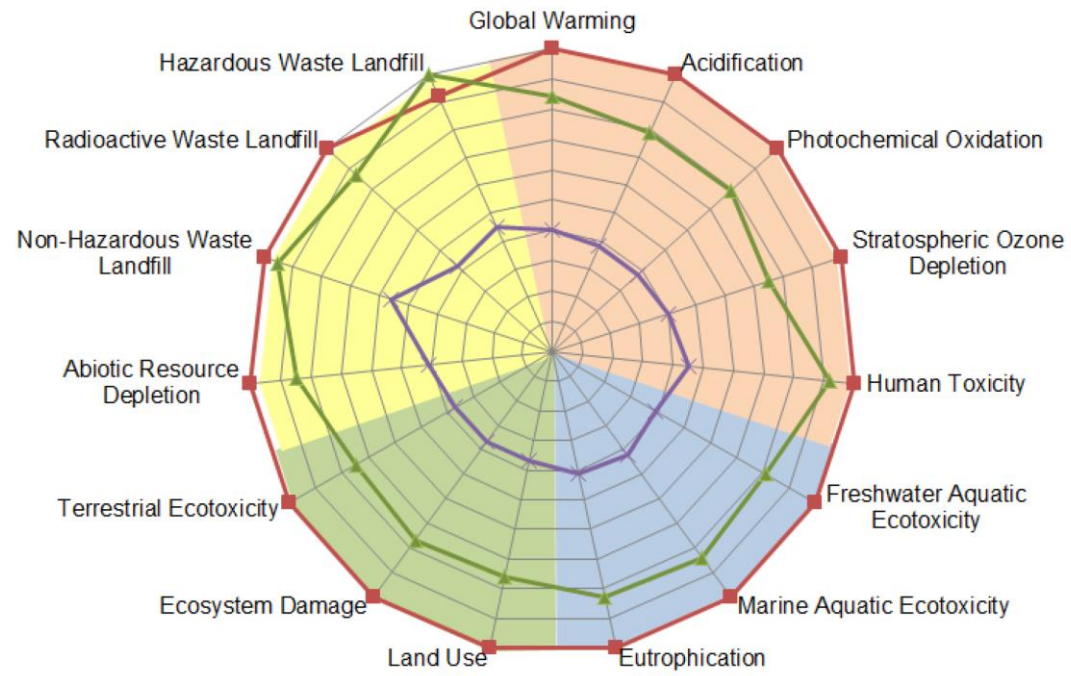


- Light extraction efficiency limited to $1/(4n^2)$ normally due to total internal reflection.
- Extraction efficiencies as high as 80-90% achieved
- State-of-the art wallplug efficiencies (power out/power in) exceed 50%

Characteristics	Incandescent	CFL	LED lamp – 2012	LED lamp – 2017
Power Consumption	60 watts	15 watts	12.5 watts	6.1 watts
Lumen Output	900 lumens	825 lumens	812 lumens	824 lumens
Efficacy	15 lm/W	55 lm/W	65 lm/W	134 lm/W
Lamp Lifetime	1500 hours	8000 hours	25,000 hours	40,000 hours
Total Lifetime Light Output	1.35 Mlm-hr	6.6 Mlm-hr	20.3 Mlm-hr*	33.0 Mlm-hr
Impacts Scalar	15.04	3.08	1.00	0.61

Resource Impacts

Air Impacts



Soil Impacts

—■— CFL —▲— LED-2012 —×— LED-2017

Water Impacts

Conclusions

- Molecular beam epitaxy:
 - Is an ultrahigh vacuum technique for deposition of high purity epitaxial layers with high uniformity, thin layers with atomic layer precision, and abrupt interfaces
 - Invented in the 1970's, and is a flexible and continually evolving technology for an increasing array of materials
 - Is a complementary technique to MOVPE for basic research, development, and commercial growth of semiconductor heterostructures.
- GaN was a challenging material to develop for epitaxial growth:
 - Gaseous group V atom
 - No lattice matched substrates (were) available
 - Difficulty p-doping the materialbut GaN solid state lighting is rapidly becoming the highest efficiency, most economical, and cleanest source of lighting for the future